



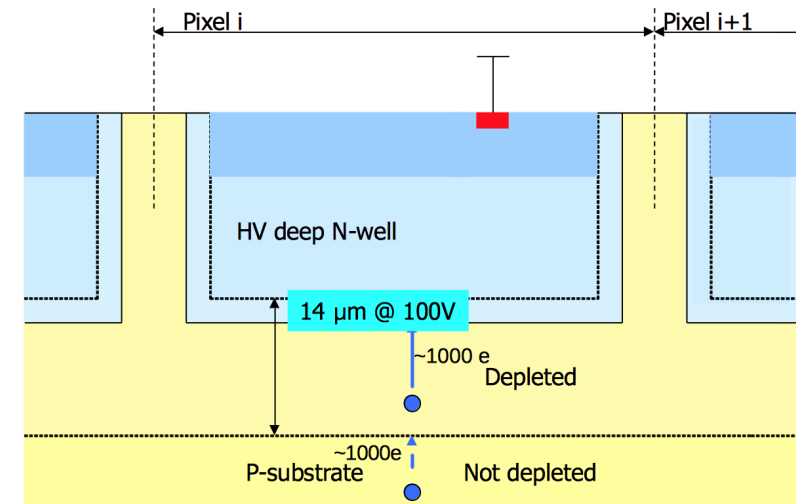
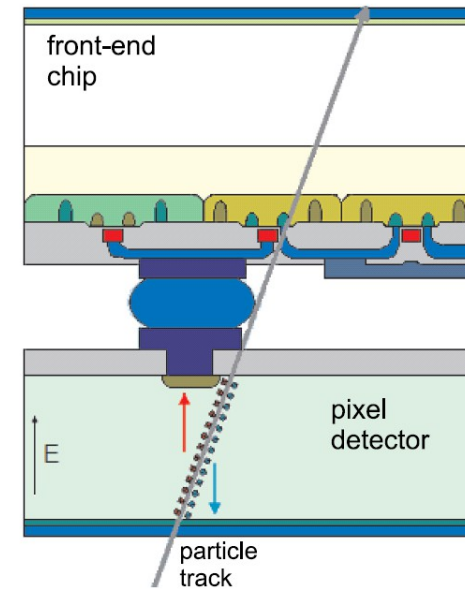
# Active Pixel Sensors for the ATLAS Upgrade - Concepts and Test Chip Results

Daniel Muenstermann

on behalf of the ATLAS HV/HR-CMOS collaboration

## Active Pixel sensors?

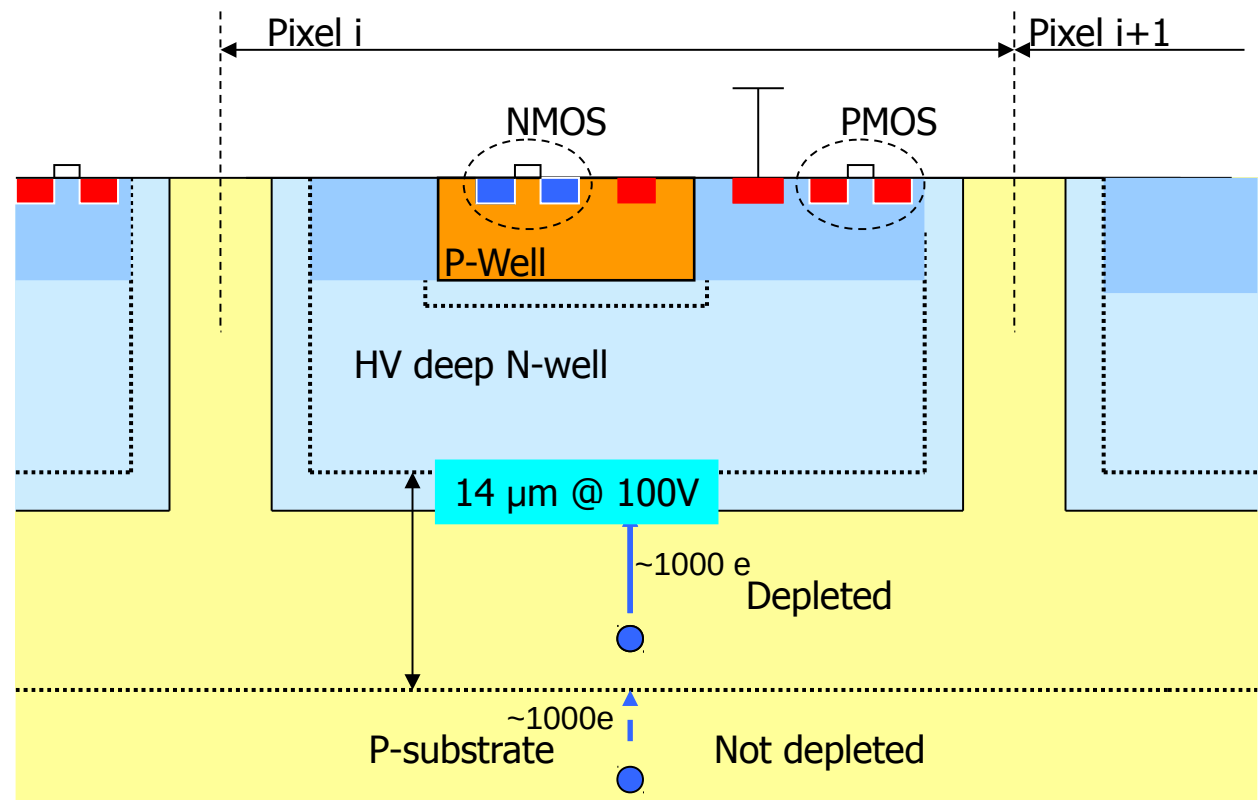
- “Classical” radiation-hard (passive) pixel sensors are usually just n-in-n or n-in-p diodes read out by bump-bonded ROCs/FEs
  - rather expensive: special 4”/6” sensor processes on high-resistive FZ substrates, bump-bonding, thinning,...
    - need to cover ~200 m<sup>2</sup> of area for HL-LHC tracker upgrades
- Could also try this in standard CMOS processes benefitting from 8” wafers and large-volume production experience
  - usually rather low-resistive substrates: 10-20 Ohm\*cm, rarely more
  - CMOS process allows for “HV”, hence breakdown voltage ~30-120V
    - ➔ depletion zone ~10 μm: signal ~1-2ke<sup>-</sup>
      - challenging for hybrid pixel readout electronics
    - disclaimer: “HV-CMOS” allows to switch “high” voltages, we don't even use this
- But it's a CMOS process, therefore we can...



The depleted high-voltage diode used as sensor (n-well in p-substrate diode)

# ...include active circuits: **Active** Pixel Sensors

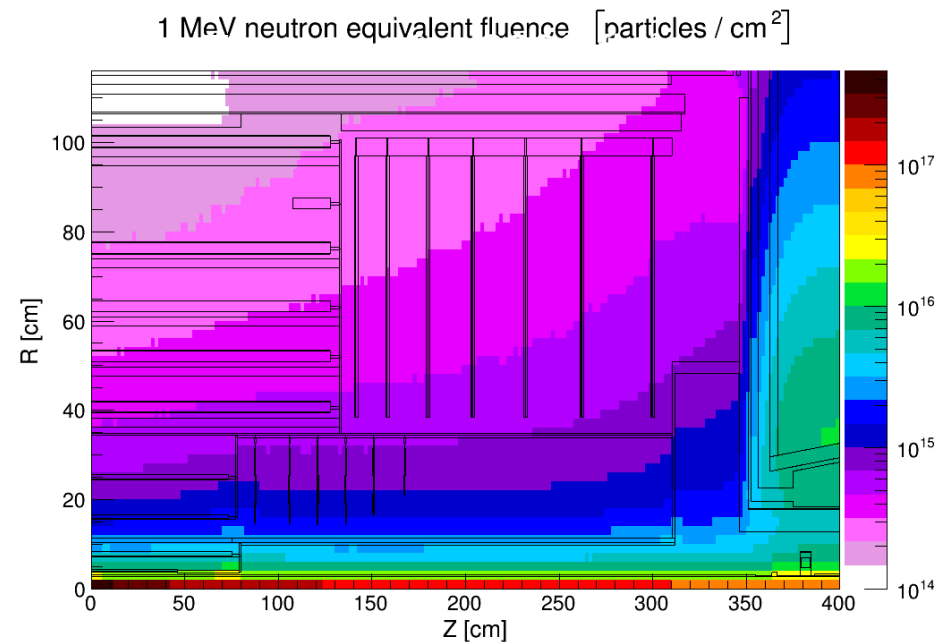
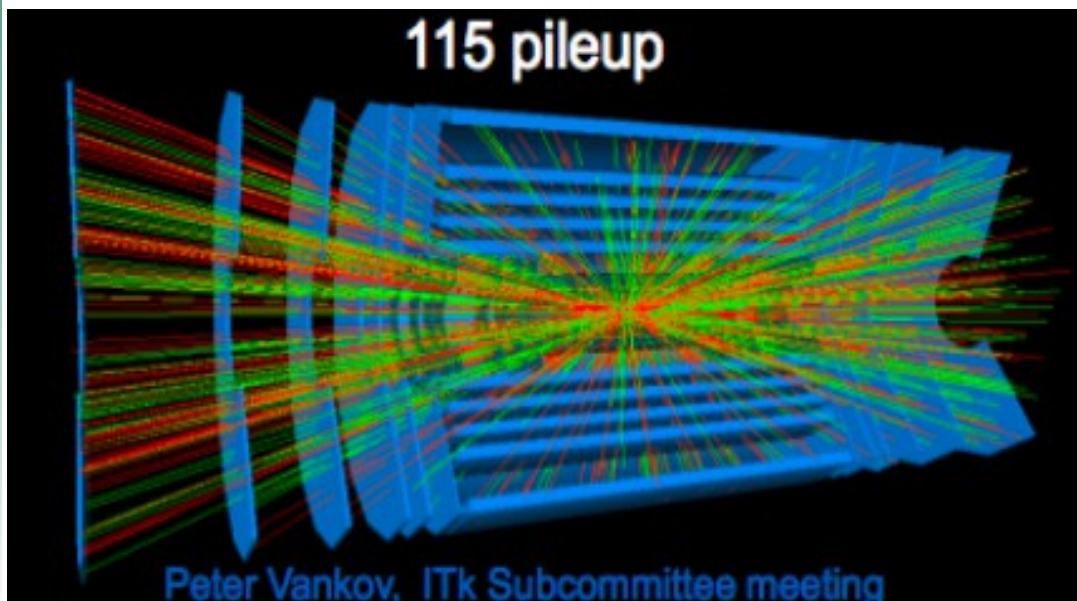
- implementation of
  - first amplifier stages
  - additional circuits: discriminators, impedance converters, logic, ...
    - careful: In its original form, no triple/quadruple wells are used → PMOS only partially usable to avoid crosstalk
- deep sub-micron technology intrinsically rad-hard, but design needs to be specific, too



CMOS electronics placed inside the diode (inside the n-well)

# Why new sensors anyway? HL-LHC and ATLAS

- Quick reminder: at LHC, the Higgs was found, but many processes require huge amount of integrated luminosity → High-Luminosity LHC (HL-LHC)
  - integrated luminosity:  $300 \text{ fb}^{-1} \rightarrow 3000 \text{ fb}^{-1}$
- What does this mean for the experiments?
  - higher occupancy:  $\sim 25 \text{ events/BC} \rightarrow 140\text{-}200 \text{ events/BC}$
  - more data rate → new readout electronics, rad-hard high-speed links
  - more radiation damage:
    - at 5 cm radius:  $\sim 2 \cdot 10^{16} n_{\text{eq}} \text{ cm}^{-2}$ ,  $\sim 1500 \text{ MRad}$
    - at 25 cm radius: up to  $10^{15} n_{\text{eq}} \text{ cm}^{-2}$ ,  $\sim 100 \text{ MRad}$ , several  $\text{m}^2$  of silicon
    - strip region: many  $10^{14} n_{\text{eq}} \text{ cm}^{-2}$ , up to  $60 \text{ MRad}$ , up to  $\sim 200 \text{ m}^2$  of silicon





## Who? “Original” ATLAS HV/HR-CMOS collaboration

- University of Bonn  
L. Gonella, T. Hemperek, F. Hübbing, H. Krüger, T. Obermann, N. Wermes
- LBNL  
M. Garcia-Sciveres
- CERN  
M. Backhaus, M. Capeans, S. Feigl, S. Fernandez Perez, M. Nessi, H. Pernegger, B. Ristic
- University of Geneva  
S. Gonzalez-Sevilla, D. Ferrere, G. Iacobucci, A. Miucci, D. Muenstermann, A. La Rosa
- University of Goettingen  
M. George, J. Große-Knetter, A. Quadt, J. Rieger, J. Weingarten
- University of Glasgow  
R. Bates, A. Blue, C. Buttar, D. Hynds
- University of Heidelberg  
C. Kreidl, I. Peric
- CPPM  
P. Breugnon, P. Pangaud, D. Fougeron, F. Bompard, J.C. Clemens, J. Liu, M. Barbero, A. Rozanov

“Original” collaboration largely based on institutes with expertise in pixel readout chips, recently also much interest from strip upgrade community, see later slides...



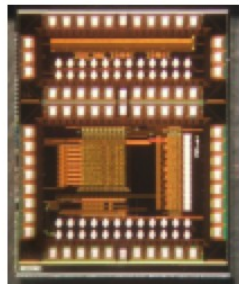
# Bottom line: How to stay rad-hard, but get cheaper?

- Ways to reduce cost: use
  - industrialised processes
  - large wafer sizes
  - cheap interconnection technologies
- **Idea: explore industry standard CMOS processes as sensors**
  - commercially available by variety of foundries
    - large volumes, more than one vendor possible
    - but: application of **drift field** required for sufficient rad-hardness
      - requires careful choice of process and design
  - 8" to 12" wafers
    - low cost per area for large volumes
    - wafer thinning quite standard
  - usually p-type Cz silicon
    - thin active layer, helpful to disentangle tracks in boosted jets and at high eta
      - requires low capacitance → small pixel
- Basic requirement: Deep n-well (→ allows high(er) substrate bias)
  - existing in many processes, e.g. even 65nm (!)
  - usually deepest in HV-CMOS → highest possible bias
  - also existing in specialised imaging processes → HR-CMOS



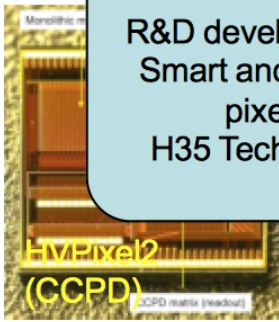
Overview: HV-CMOS – too many test chips...

Active Pixel Sensors – HV-CMOS

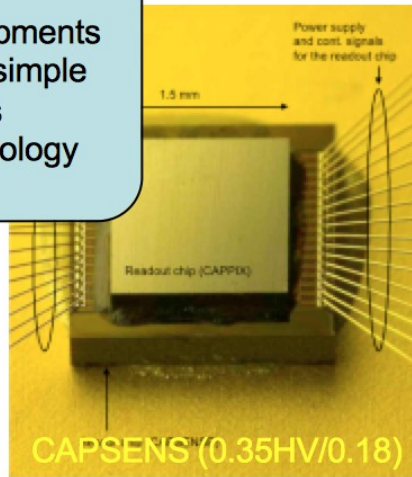


HVPixel1 (H35)

R&D developments  
Smart and simple  
pixels  
H35 Technology



HVPixel2 (CCPD)

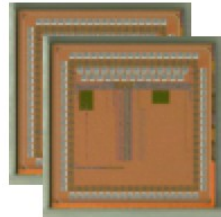


CAPSENS (0.35HV/0.18)

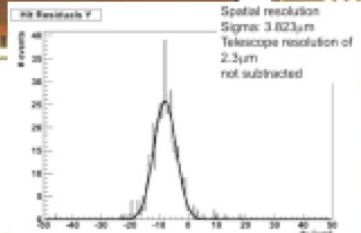
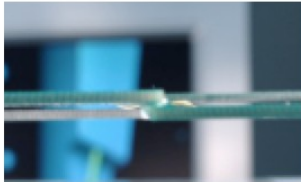
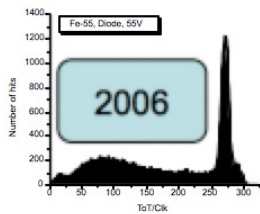


HVPixel (H35)

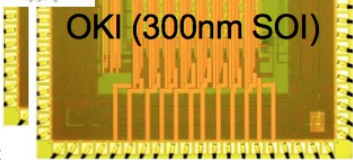
R&D developments  
H18 and 65nm  
technology



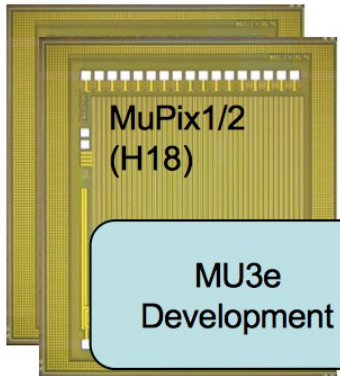
SDS (65nm)



OKI SOI

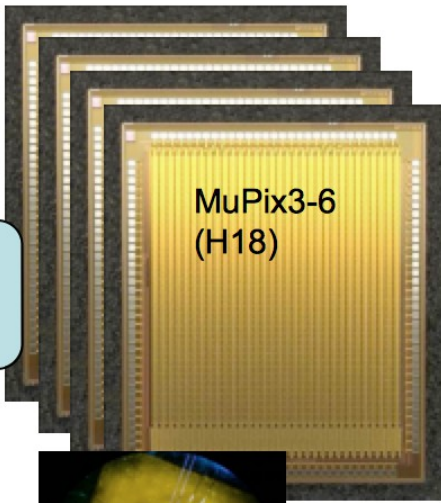


OKI (300nm SOI)

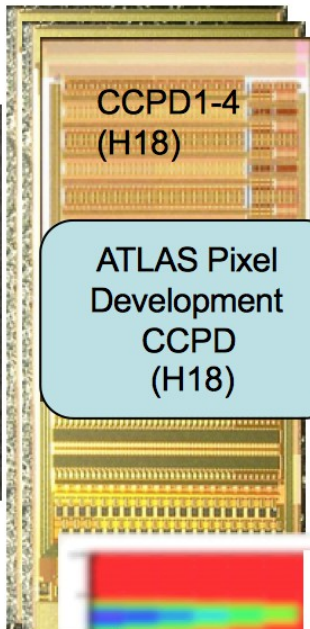


MuPix1/2 (H18)

MU3e  
Development

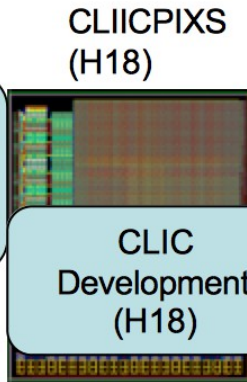


MuPix3-6 (H18)



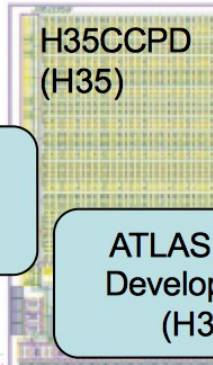
CCPD1-4 (H18)

ATLAS Pixel  
Development  
CCPD (H18)



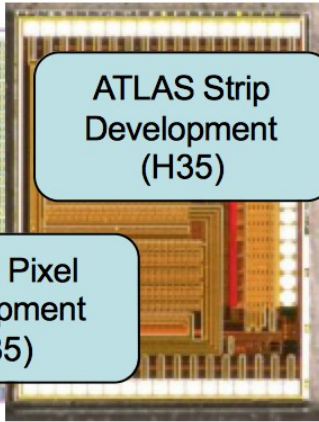
CLICPIXS (H18)

CLIC  
Development  
(H18)

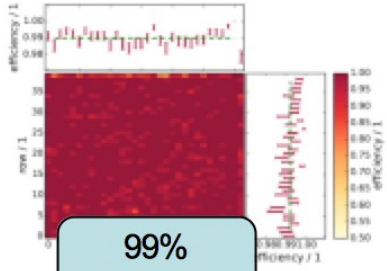


H35CCPD (H35)

ATLAS Pixel  
Development  
(H35)



ATLAS Strip  
Development  
(H35)

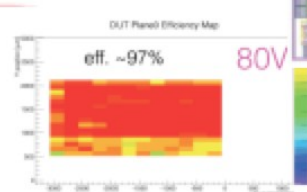
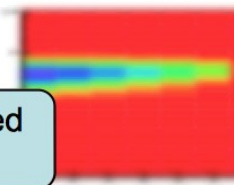


99%  
efficiency



Thinned  
chips

Irradiated  
chip



eff. ~97%  
80V

## The beginning: proof of concept prototypes

- Several early test-chips by Ivan Peric (most in AMS 350 nm HV-CMOS process)

SDA with sparse readout  
("intelligent" CMOS pixels)  
HV2/MuPixel chip

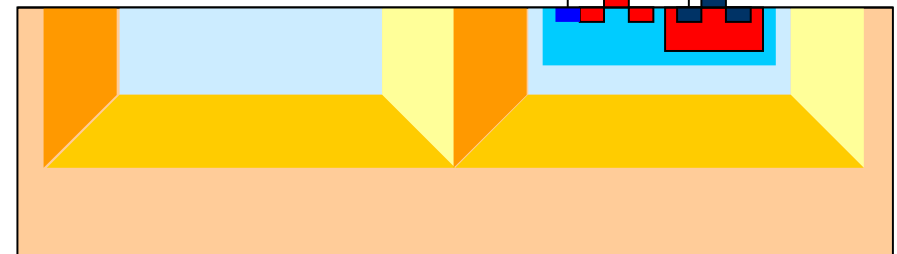
- baseline for  $\mu 3e$  experiment at PSI
- see poster of D. Wiedner!

SDA with frame readout  
(simple PMOS pixels)  
HVM chip

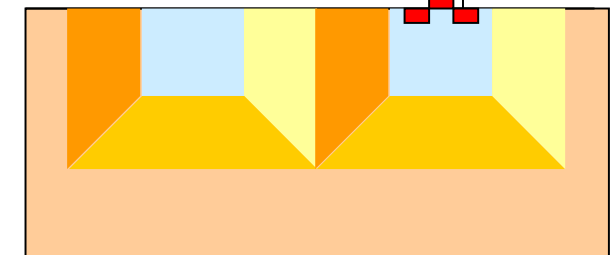
SDA with capacitive readout  
("intelligent" pixels)  
Capacitive coupled pixel  
detectors  
CCPD1 and CCPD2 detectors

- ATLAS and CLIC

Binary information

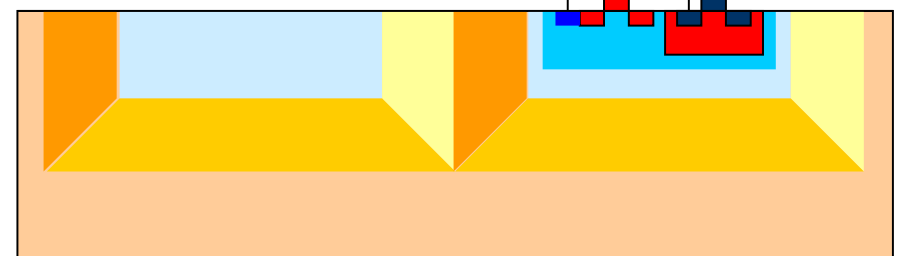


Analog information



RO chip

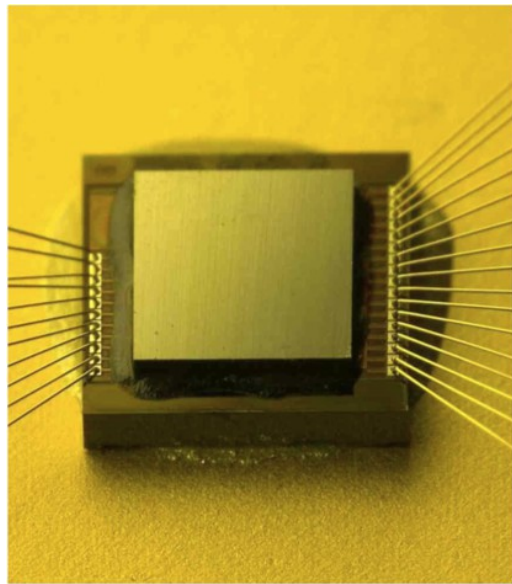
Analog information







## Prototype summaries



First chip – CMOS pixels  
 Hit detection in pixels  
 Binary RO  
 Pixel size 55x55µm  
 Noise: 60e  
 MIP seed pixel signal 1800 e  
 Time resolution 200ns

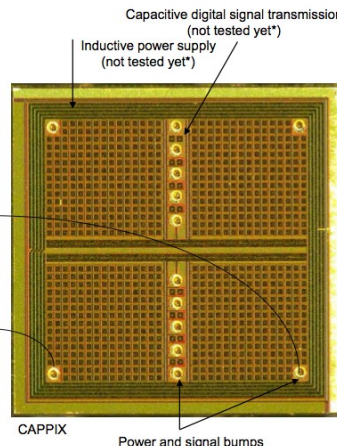
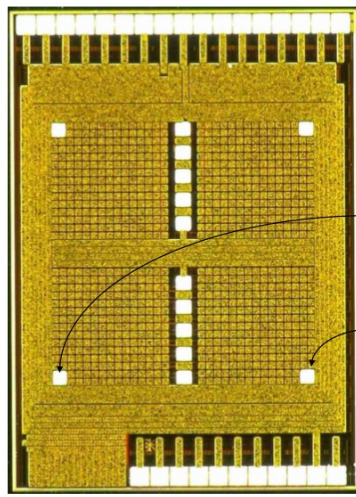
Bumpless hybrid detector  
**CCPD1 Chip**  
 Bumpless hybrid detector  
 Based on capacitive chip to chip  
 signal transfer  
 Pixel size 78x60µm  
 RO type: capacitive  
 Noise: 80e  
 MIP signal 1800e

Frame readout - monolithic  
**PM1 Chip**  
 Pixel size 21x21µm  
 Frame mode readout  
 4 PMOS pixel electronics  
 128 on chip ADCs  
 Noise: 90e  
 Test-beam: MIP signal 2200e/1300e  
 Efficiency > 85% (timing problem)  
 Spatial resolution 7µm  
 Uniform detection

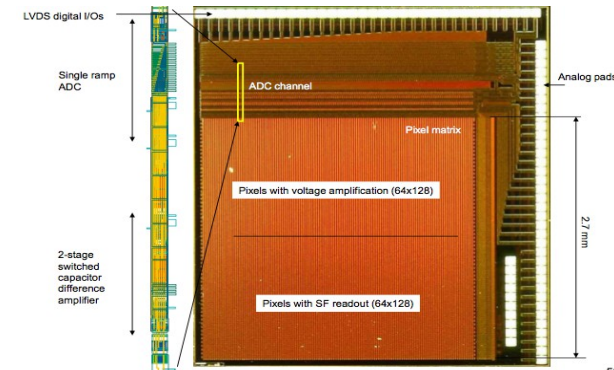
**CCPD2 Chip**  
 Edgeless CCPD  
 Pixel size 50x50µm  
 Noise: 30-40e  
 Time resolution 300ns  
**SNR 45-60**

**PM2 Chip**  
 Noise: 21e (lab) - 44e (test beam)  
**Test beam: Detection efficiency 98%**  
**Seed Pixel SNR ~ 27**  
**Cluster Signal/Seed Pixel Noise ~ 47**  
**Spatial resolution ~ 3.8 µm**

Irradiations of test pixels  
**60MRad – SNR 22 at 10C (CCPD1)**  
 **$10^{15} n_{eq}/cm^2$  – SNR 50 at 10C (CCPD2)**



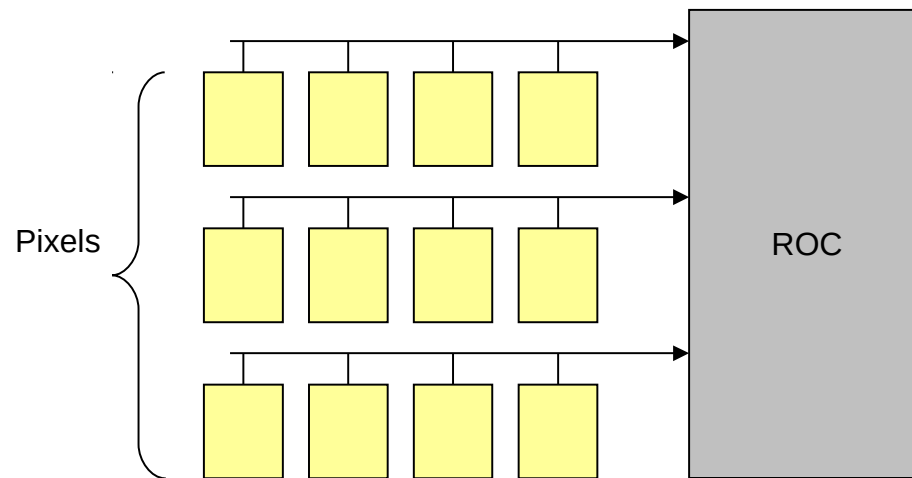
\*If work, these features would allow to operate the readout chip without any mechanical contact



# From MAPS to active sensors

- Existing prototypes were not suitable for HL-LHC, mainly because
  - readout too slow, no trigger handling/buffering
  - time resolution not compatible with 40 MHz operation
  - high-speed digital circuits might affect noise performance
- Idea: use HV-CMOS as active sensor in combination with a (possibly modified) existing fast/"LHC" readout chip
  - makes use of highly optimised readout circuits
  - can be seen as first step towards a sensor being integrated into a 3D-stacked readout chip (not only analogue circuits but also charge collection)
- Basic building blocks: *small* pixels (low capacitance, low noise)
  - can be connected in any conceivable way to optimise readout granularity, e.g.

- (larger) pixels
- strips





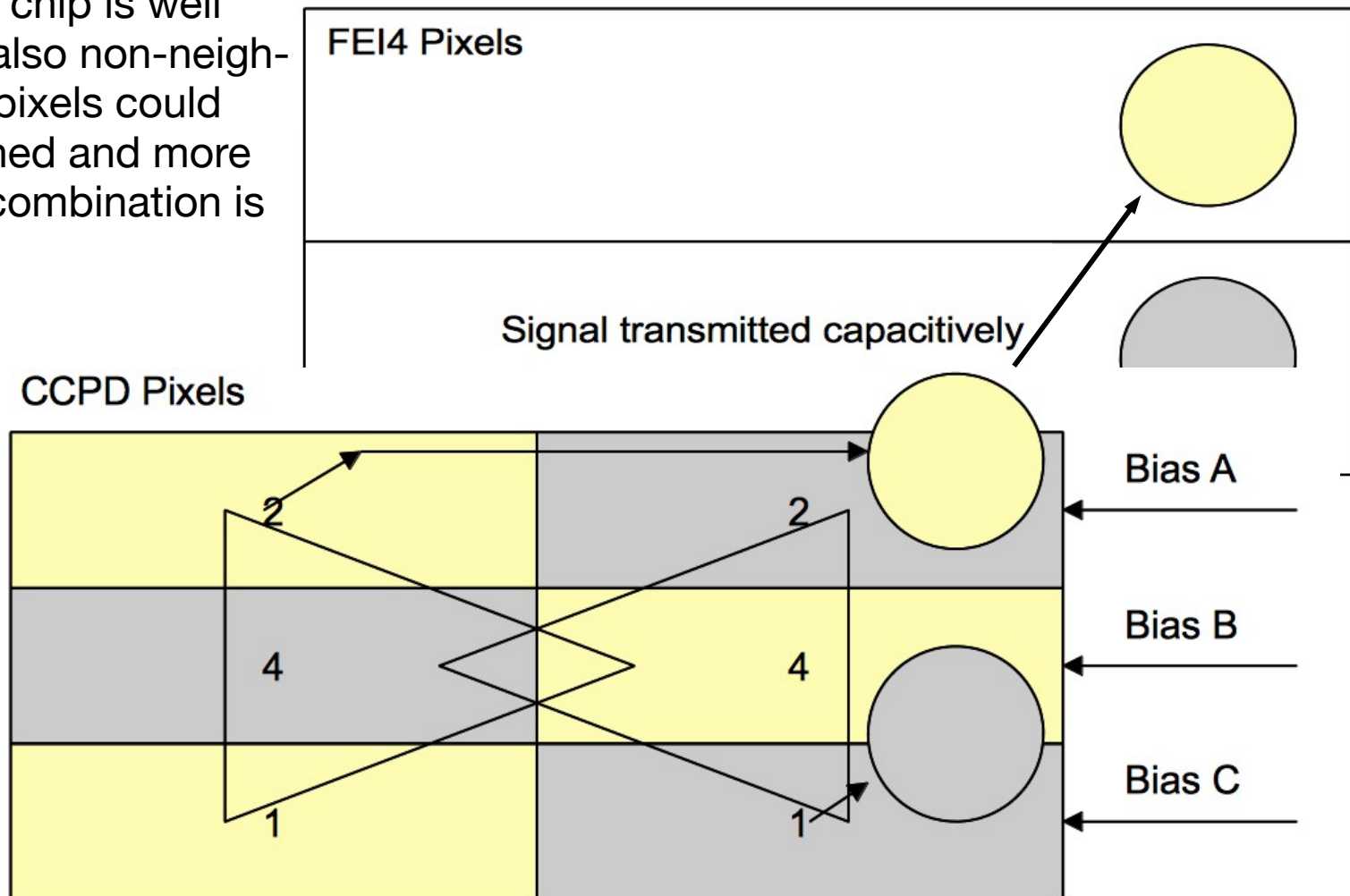
## ATLAS: AMS H18 HV-CMOS

- Austria Micro Systems HV-CMOS process with 180 nm feature size
  - expected more radiation hardness wrt 350 nm
  - less power consumption/faster amplifiers to satisfy LHC timing requirements
- “HV2FEI4”-chip:
  - biasing of substrate to ~60-100V possible
  - substrate resistivity  $\sim 10 \text{ Ohm}\cdot\text{cm} \rightarrow N_{\text{eff}} > 10^{14}/\text{cm}^3$ 
    - radiation induced  $N_{\text{eff}}$  insignificant even for innermost layers
  - depletion depth theoretically in the order of  $10 \mu\text{m}$ 
    - drift signal  $\sim 1 \text{ ke}^-$
  - readout via existing pixel chip (ATLAS FE-I4)
    - preamplifier and discriminator in pixel cell at the expense of increased crosstalk and noise
  - in principle also strip-like readout possible, position along virtual strip encoded in pulse height (analogue sub-pixel encoding)



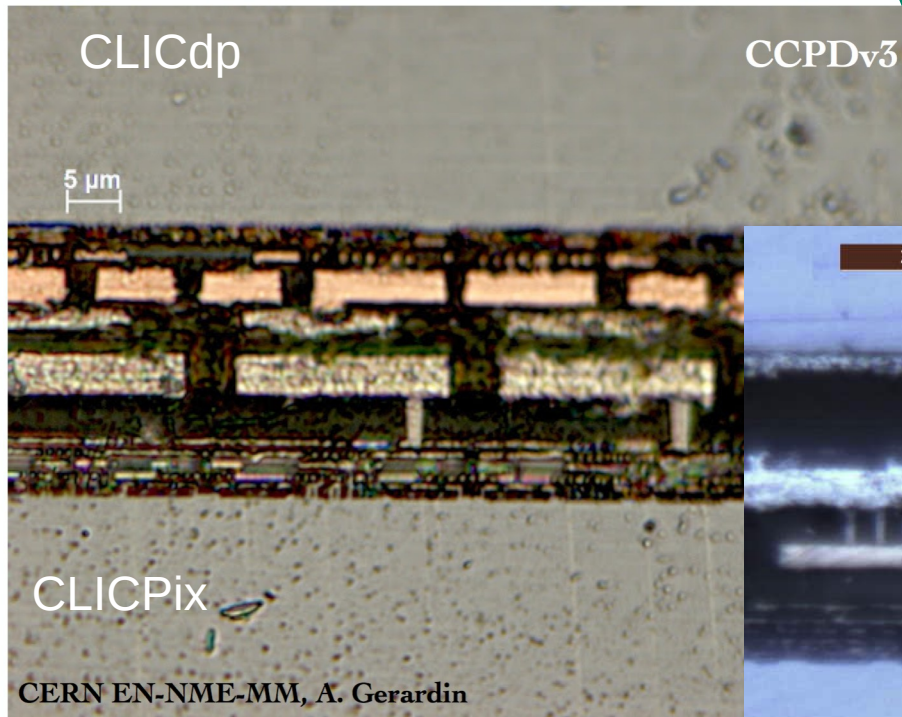
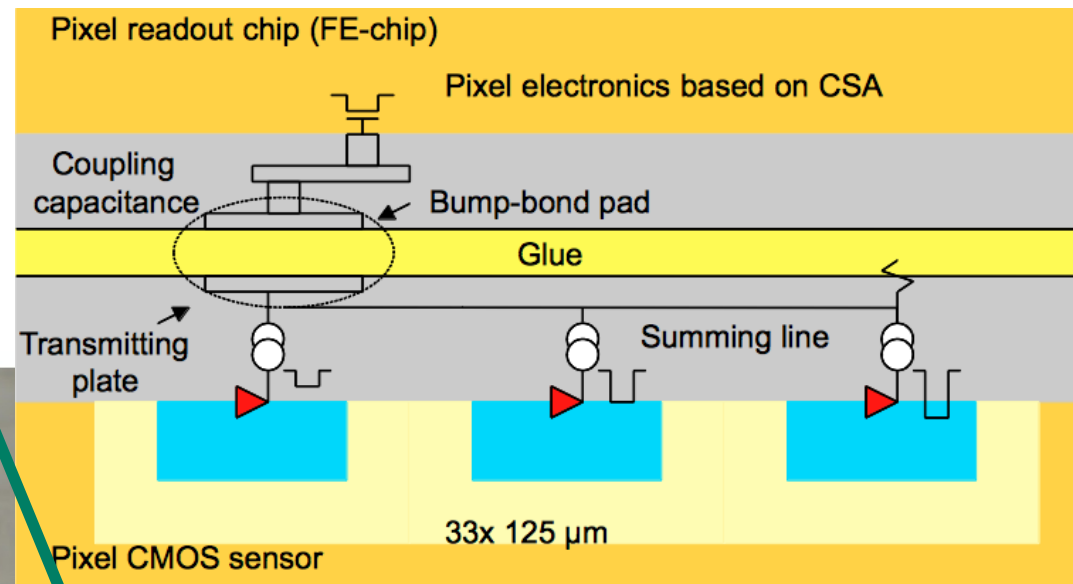
# Pixels: sizes and combinations

- Possible/sensible pixel sizes: 20x20 to at most 25x250  $\mu\text{m}$ 
  - 50x250  $\mu\text{m}$  (current ATLAS FE-I4 chip) too large
  - combine several sensor “sub-pixels” to one ROC-pixel
    - sub-Pixels encode their address/position into the signal as pulse-height-information instead of signal proportional to collected charge
    - routing on chip is well possible, also non-neighbour sub-pixels could be combined and more than one combination is possible



## Pixels: bonding?

- Bump-bonding expensive and difficult for thin assemblies (bow)
- Alternatives: wafer-to-wafer bonding, gluing
  - amplification possible, hence AC transmission not a problem at all
  - variations in glue thickness can be handled by tuning procedures and offline corrections if necessary
  - no thermal bowing during curing
  - glue layer thicknesses  $< 10 \mu\text{m}$  were achieved across  $2 \times 2 \text{cm}$  using low-viscosity epoxies



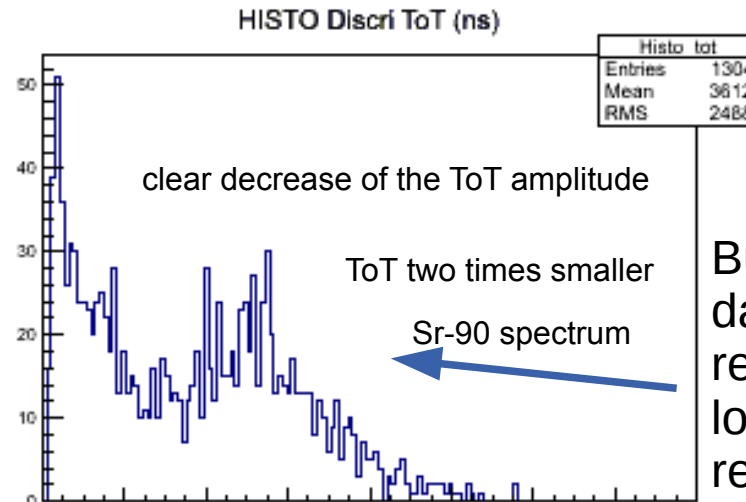
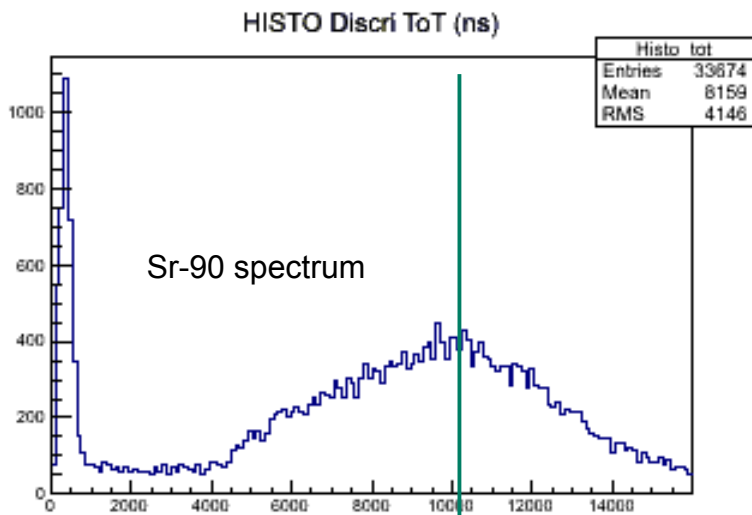


## HV2FEI4: standalone characterisation

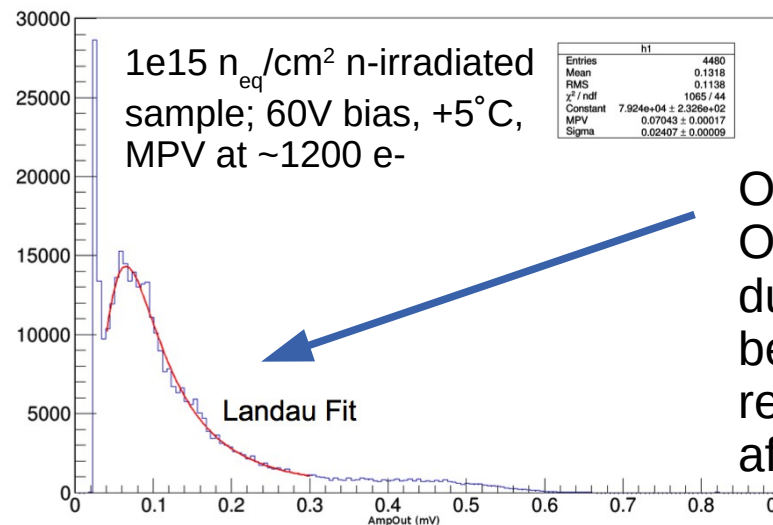
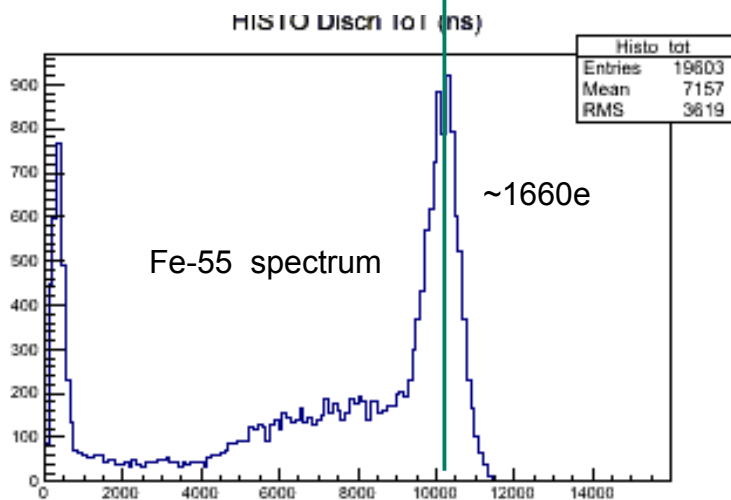
- Irradiations at CERN/PS, with reactor neutrons and with x-rays
  - on special PCB allowing for remote operation, HV2FEI4 powered and read-out during irradiation

un-irradiated device

CCPD9 irradiated at 80 MRad



Bulk and ionisation damage: mix of reduced signal and lower amplification: reduced to ~50% after irradiation

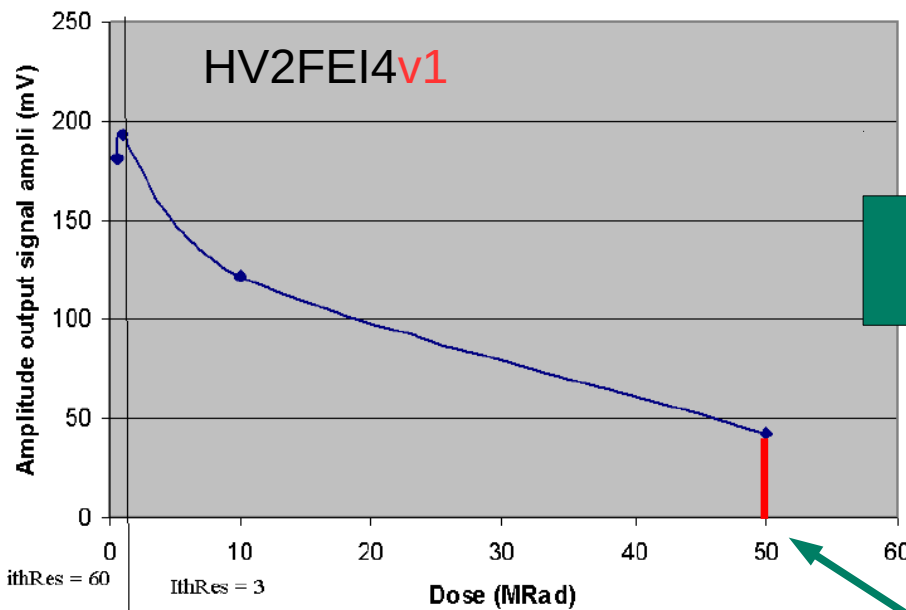


Only bulk damage: Only loss of signal due to diffusion being eliminated: reduced to ~70% after irradiation

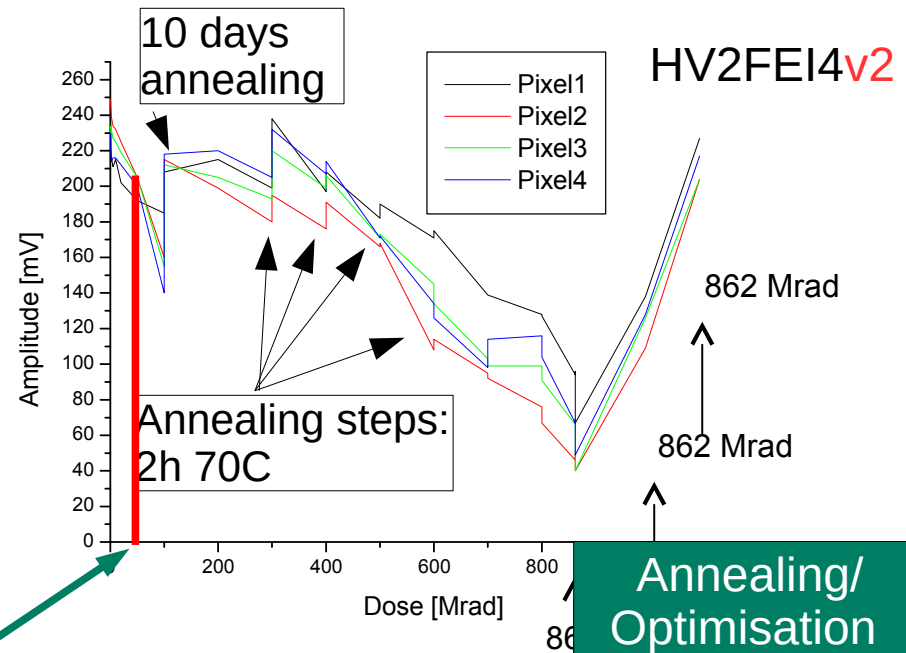


## HV2FEI4 irradiation: dose effects

- Radiation effects due to dose, could be reproduced by x-ray irradiation
    - HV2FEI4v1: deliberately rad-soft/standard design to see how far it lasts
    - HV2FEI4v2: different rad-hard designs (guard rings, circular transistors, ...)
  - Signal amplitude clearly much more stable
    - irradiated up to 862 Mrad (!), drop visible after ~500 MRad
      - dose rate effect, annealing brings signal back to ~100%
- ➔ rad-hardness significantly improved, hadron irradiations to follow



HV2FEI4v1 irradiated with x-rays  
Amplifier gain loss

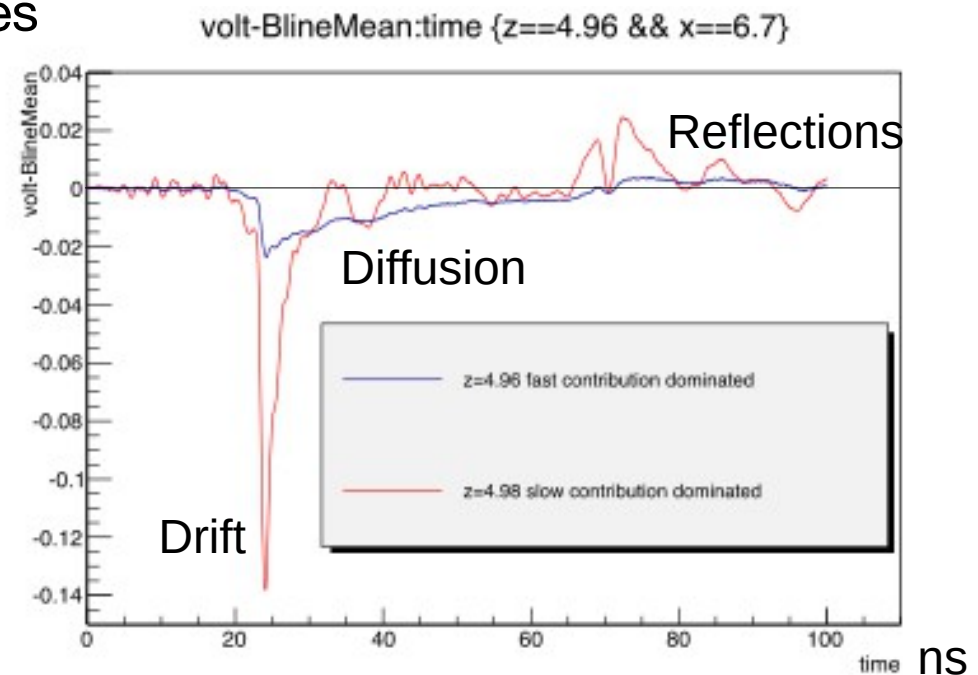


HV2FEI4v2 irradiated with x-rays  
Amplifier gain loss  
Rad hard pixels



## HV2FEI4 irradiation: fluence effects

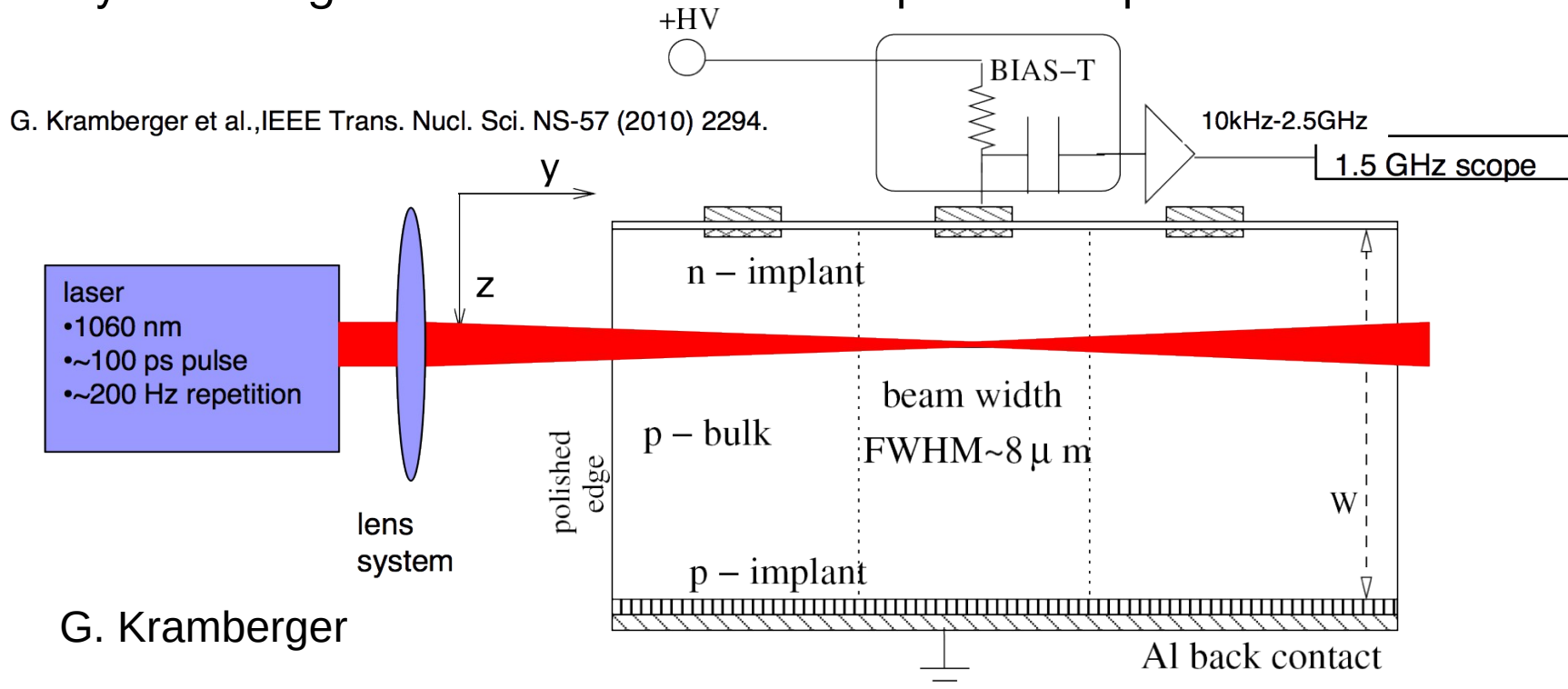
- Numerically, depletion depth for 10 Ohm\*cm substrate is about 10  $\mu\text{m}$  at 100V of bias
  - Classically, this should yield less than 800 electrons of collected charge
  - We observe  $\sim 1500\text{-}1900\text{ e}^-$  before irradiation – large diffusion component?
  - Still  $\sim 1200\text{ e}^-$  after irradiation to  $1\text{e}15\text{ neq/cm}^2$  using (slow) in-pixel charge-sensitive amplifiers
    - Diffusion should be ruled out at that fluence, other effects?
- → Edge-TCT
  - can distinguish (fast) drift from (slow) diffusion
  - can measure charge collection zones
- Variables
  - Transients (Current vs. time)
  - Integrals (Charge vs. position)
- Credits: Results also obtained as part of the RD50 collaboration





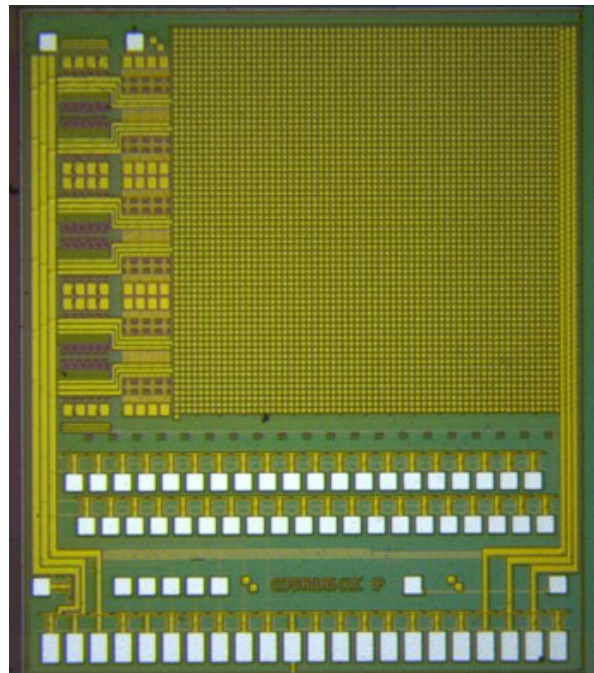
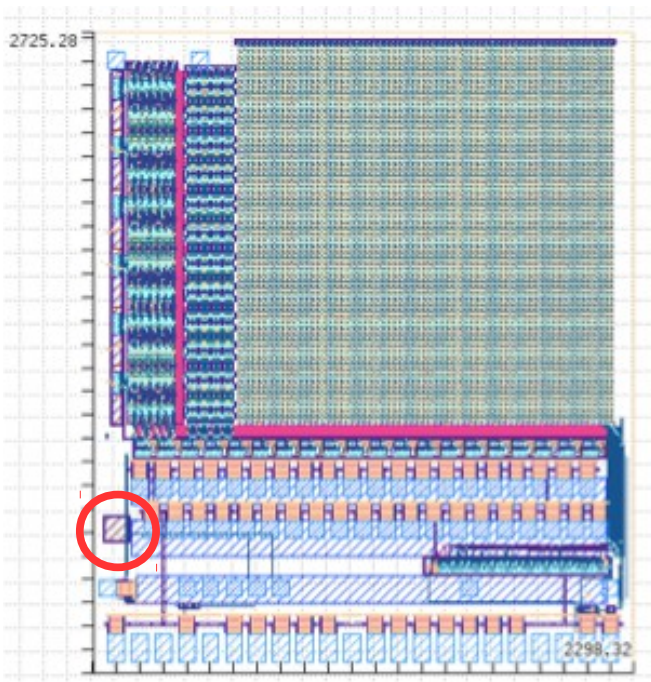
### What is edge-TCT?

- TCT: Transient Current Technique, i.e. observe the time-resolved charge collection generated by MIP, alpha or laser pulse
  - usually lasers are used because of their constant charge deposition per pulse → can average many samplings, get rid of noise
  - can scan the sensor to study inter-pixel boundary efficiencies etc.
  - short signals, so charge-sensitive preamps usually too slow, need fast current-based amplifiers → external, discrete, specialised amps
- edge: shooting in through the side-wall of the sensor with a IR laser
  - can study the charge collection at different depths → depletion?



## Samples

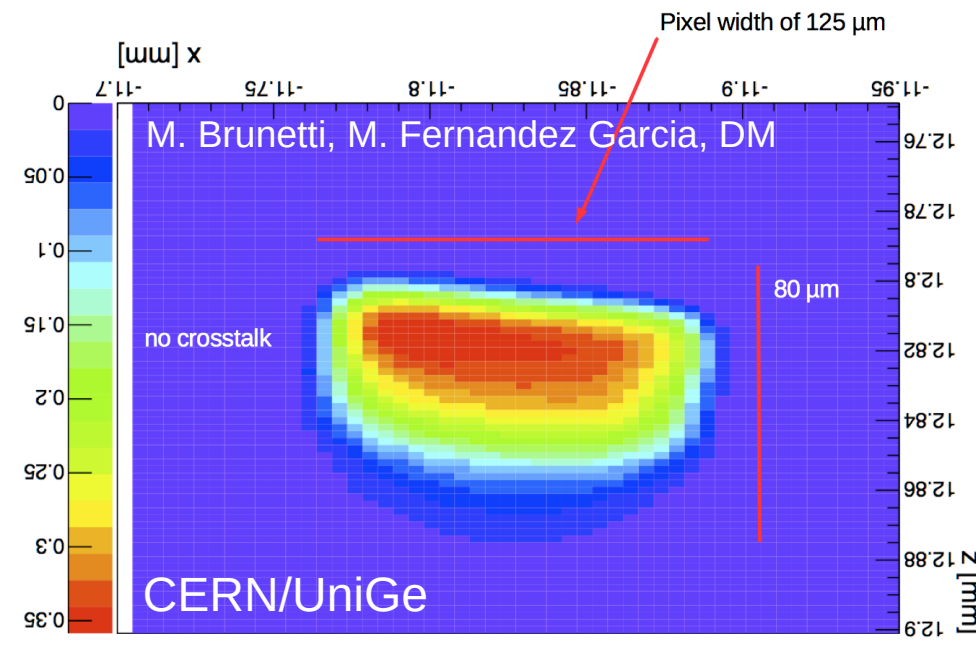
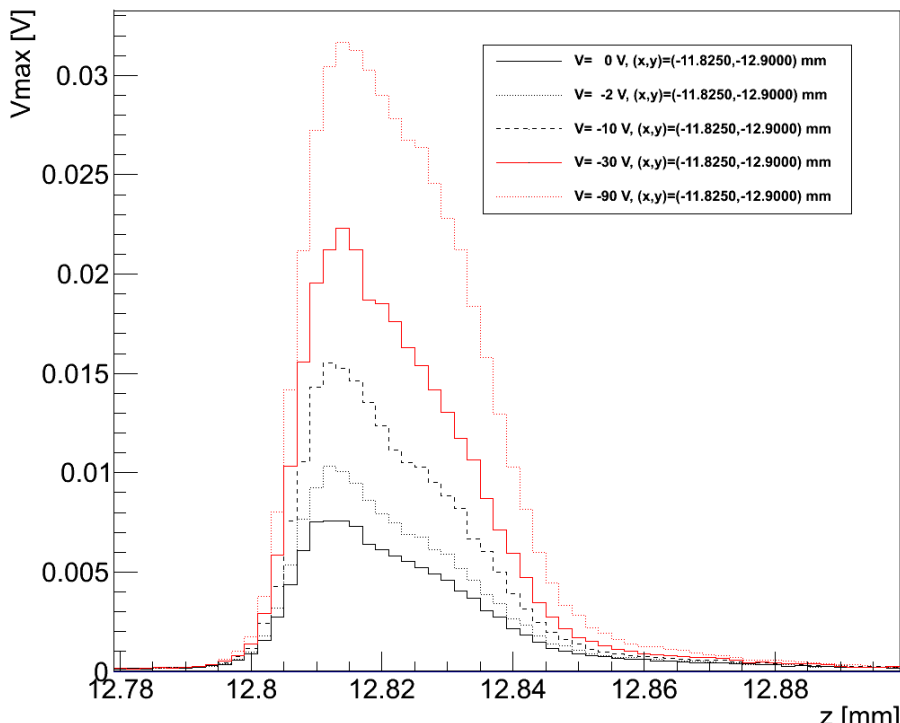
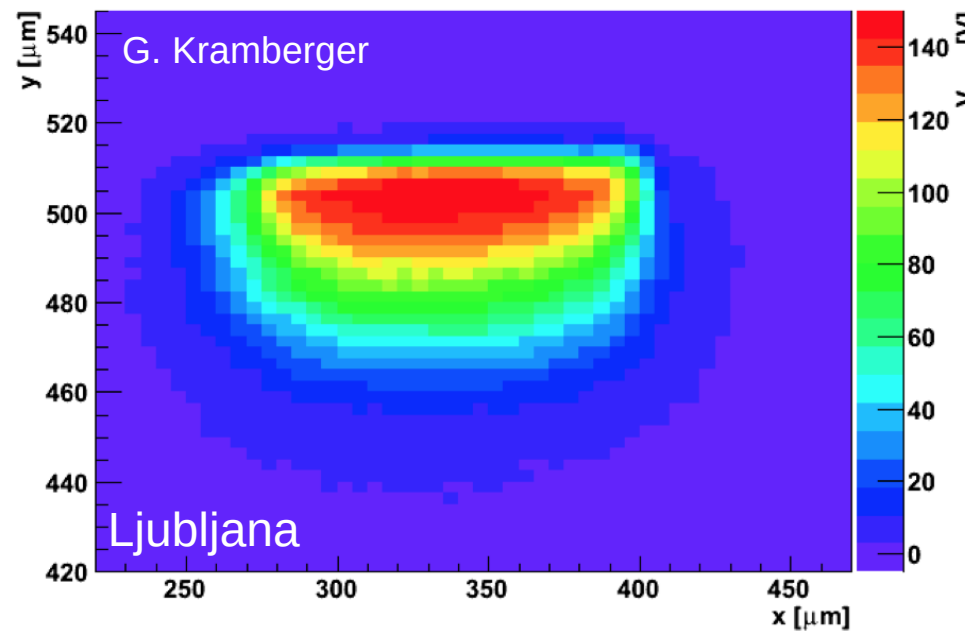
- Measurements on AMS H18 HV2FEI4 v2 and v3
  - v2: Only charge-sensitive preamplifier output accessible
    - 33 x 125  $\mu\text{m}$  pixel with full electronics
    - very slow risetime compared to expected signal collection time
    - difficult assessment of drift/diffusion contribution
  - v3: one dedicated passive 100 x 100  $\mu\text{m}$  diode accessible
    - no neighbours, so beware of edge effects
    - also irradiated samples available, for today:  $1\text{e}15$  neq/cm<sup>2</sup>



## v2 results: CERN/UniGe, Ljubljana

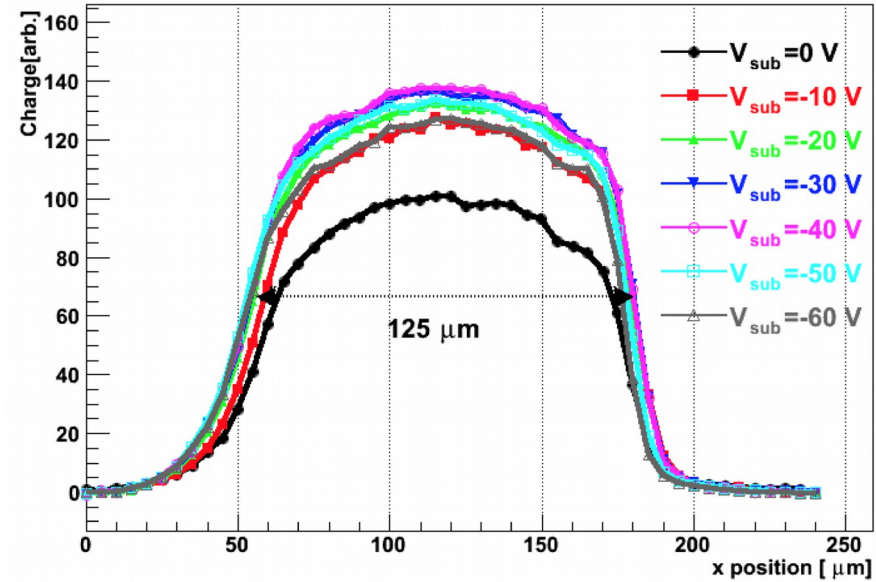
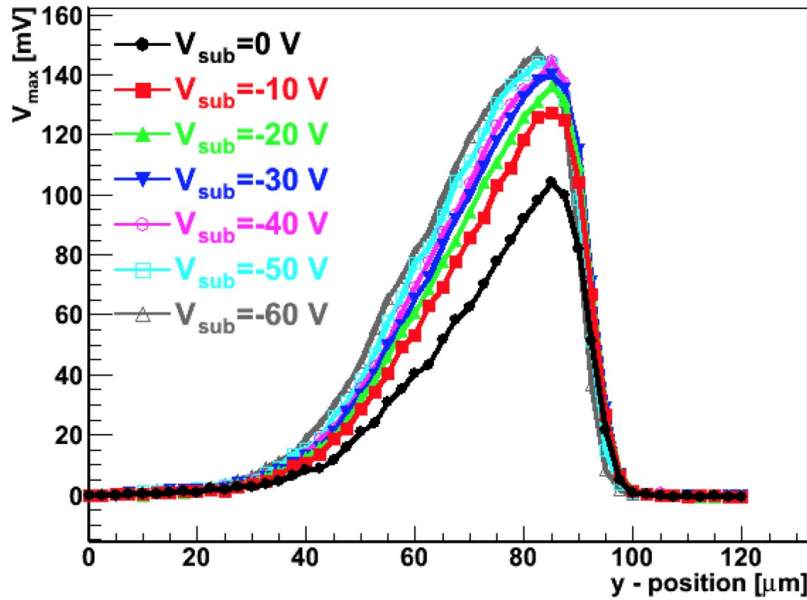
- Find full pixel length, extension of charge collection zone up to almost 80  $\mu\text{m}$  depth with significant contributions to 20-30  $\mu\text{m}$
- Preamps generally too slow to easily discriminate between drift and diffusion
  - Ljubljana analysis effort: risetime to reach 50% of full charge

$V_{\text{sub}} = -60 \text{ V}$

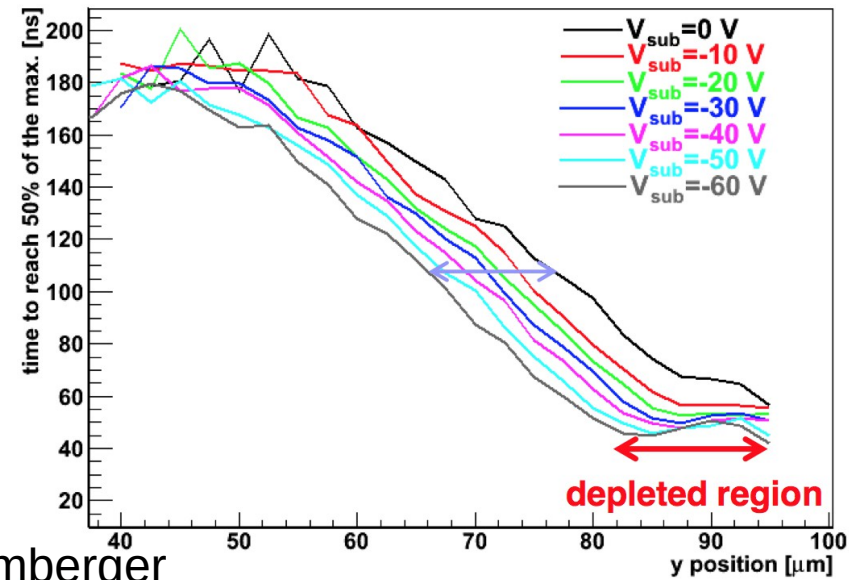
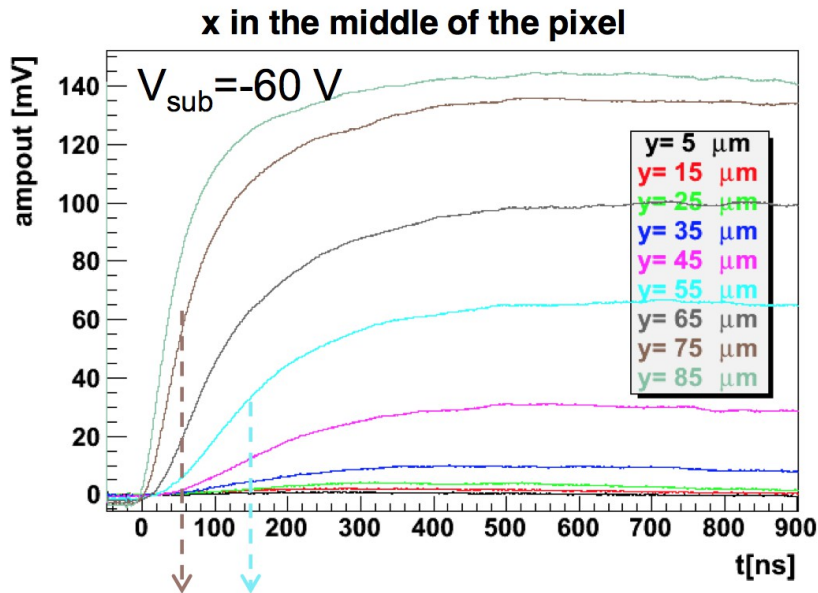




- Improved analysis effort: time to reach 50% of the charge

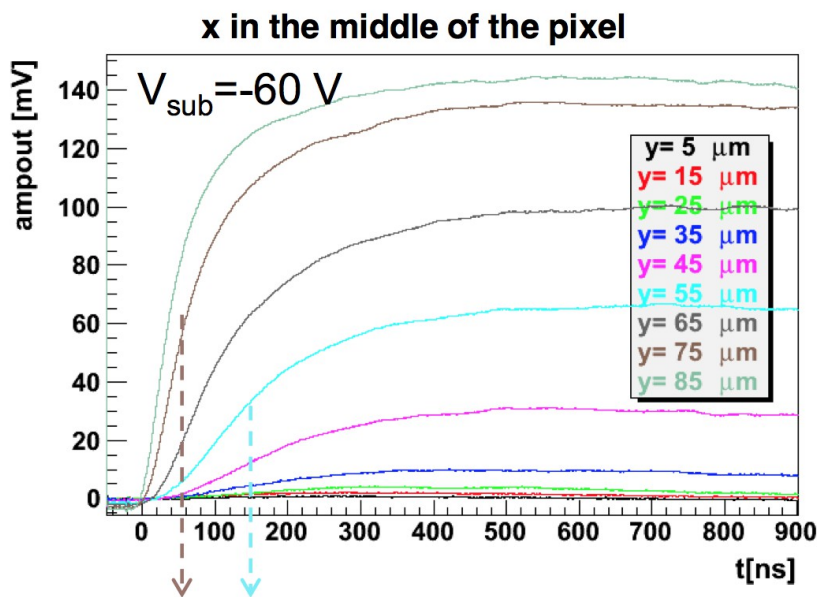


$t_{th}$  as a function of y position at different voltage:

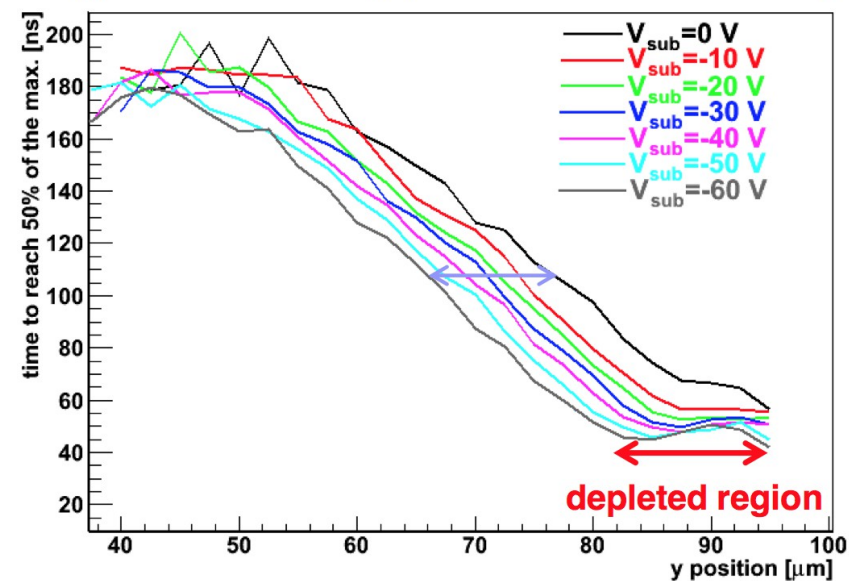


## v2: Ljubljana

- Repeated measurement, but additional analysis effort: time to reach 50% of the charge
- Conclusions:
  - ~7 $\mu\text{m}$  depletion zone
  - 35% of signal due to drift at -60V
- Rather indirect way of measurement, so...



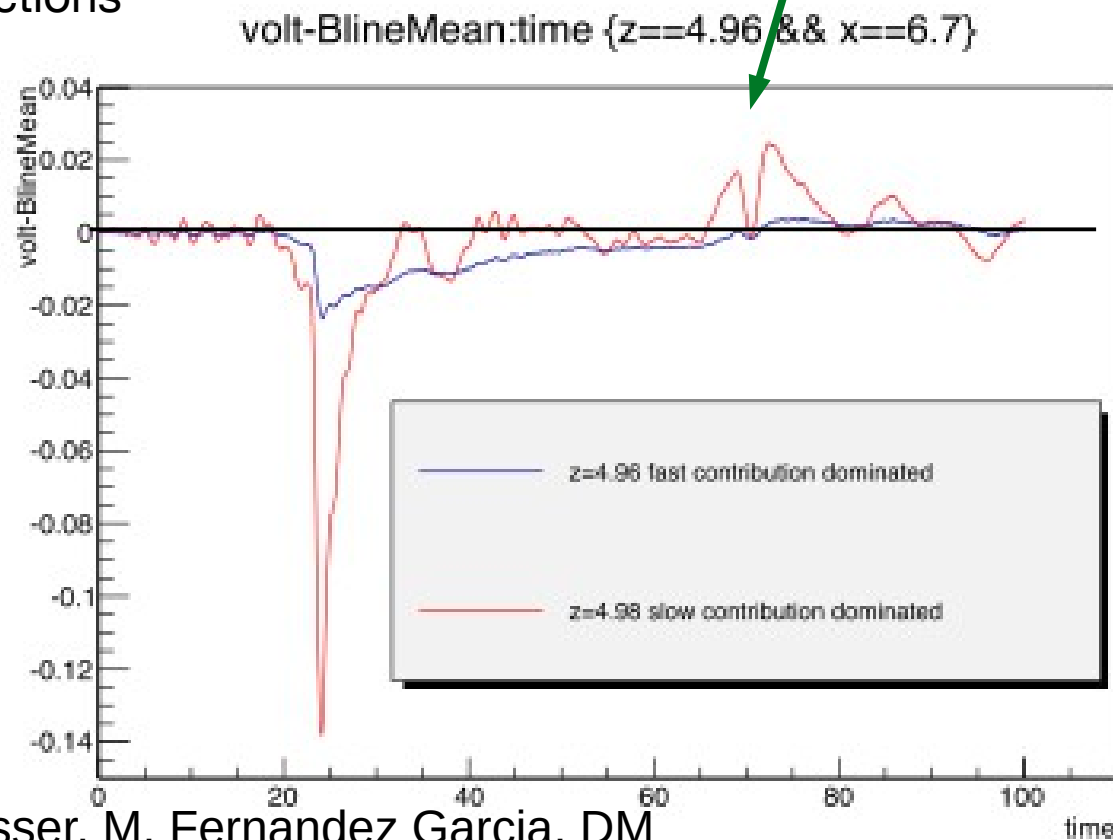
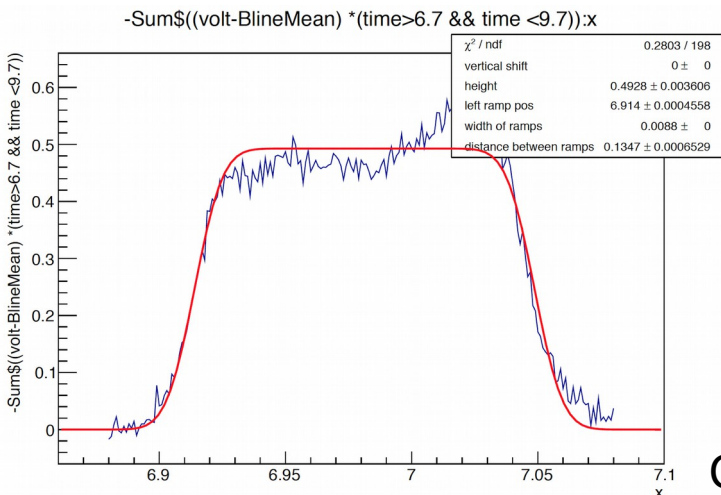
$t_{th}$  as a function of y position at different voltage:





## v3

- Direct access to 100 x 100  $\mu\text{m}$  passive diode, outside of matrix, no direct neighbours
- used different high-bandwidth (GHz) current-sensitive amplifiers
  - keep in mind that now the transient is current, integral is charge
  - do suffer from non-matched impedances  $\rightarrow$  many reflections
    - working on an improved PCB, put 5m cable in between  $\rightarrow$  big reflection after 50ns
    - diffusion slow, not many reflections
- Divided contributions:
  - fast:  $< \sim 3\text{ns}$
  - slow: 3- $\sim 70\text{ns}$
- Laser width:  $\sim 9 \mu\text{m}$  (x-scan)

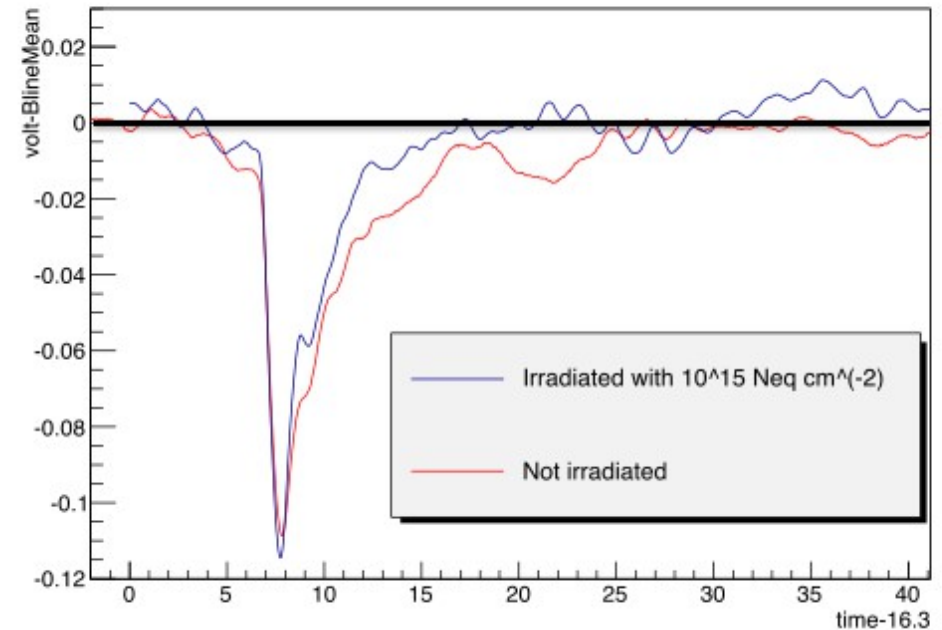




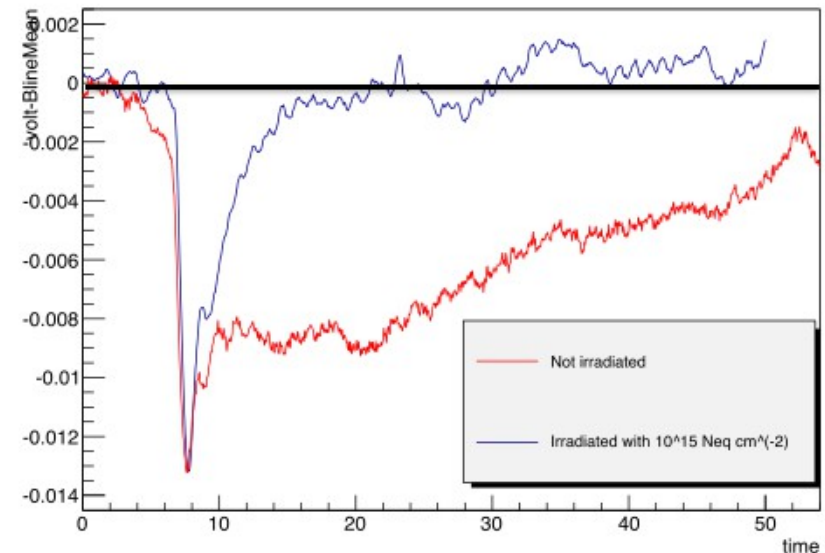
## v3

- Comparing transients
- Top: inside drift zone
  - similar, irradiated returns to baseline faster → less signal? Small diffusion component from lateral diffusion?
- Bottom: inside diffusion zone
  - smaller absolute scale!
  - lots of slow diffusion before irradiation, only some drift after irradiation

volt-BlineMean:time-16.3 {x==6.71 && z==4.97}

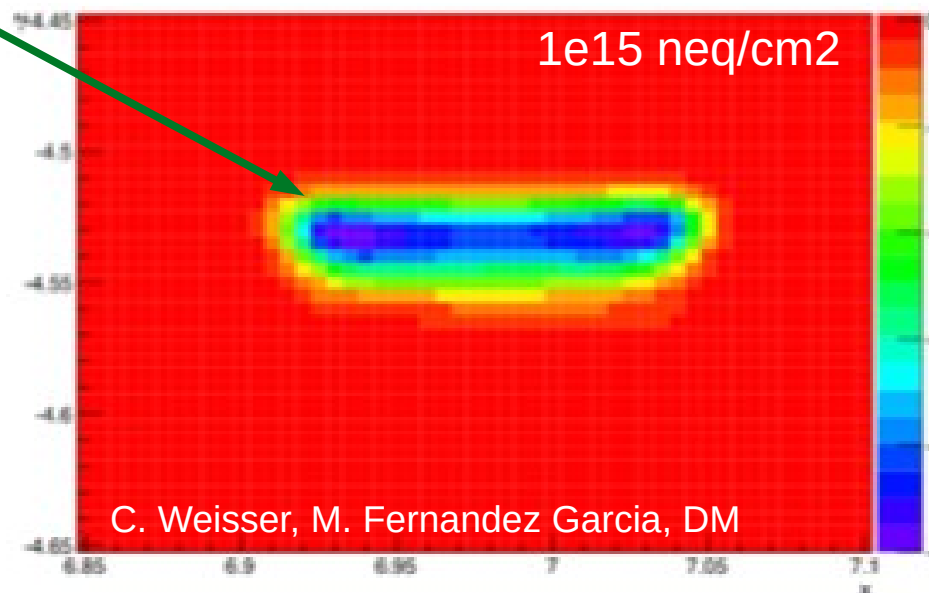
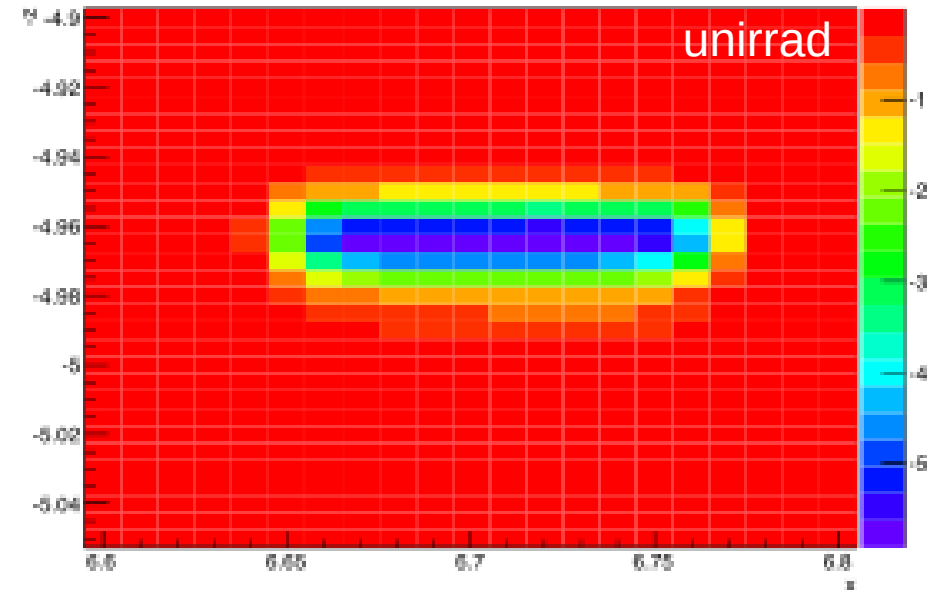


volt-BlineMean:time {x==6.98 && z ==4.56}



## v3

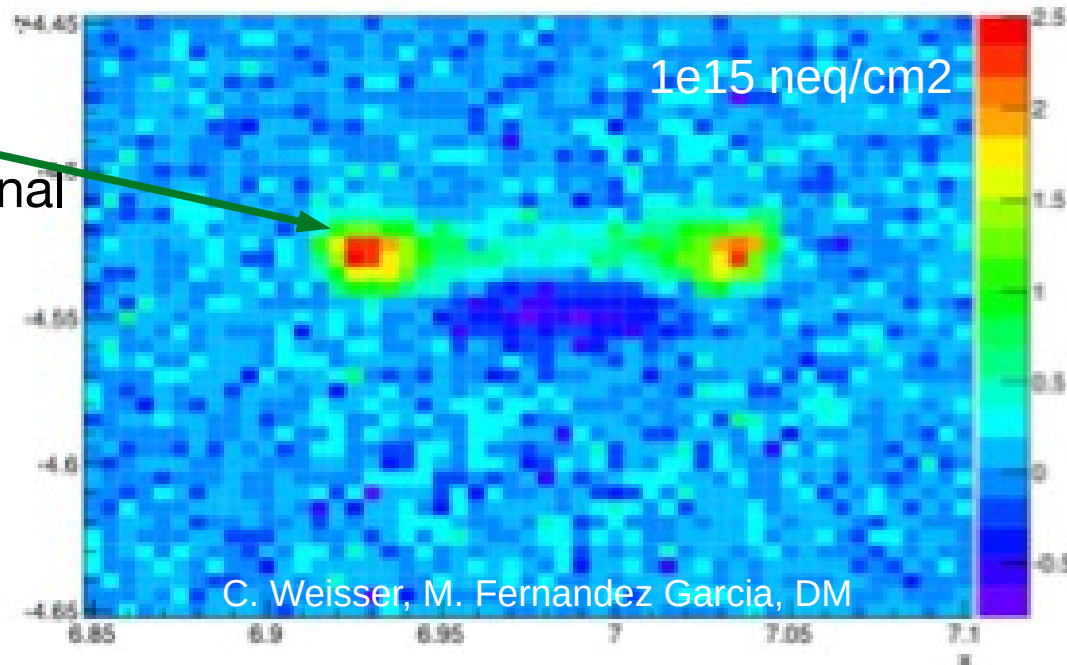
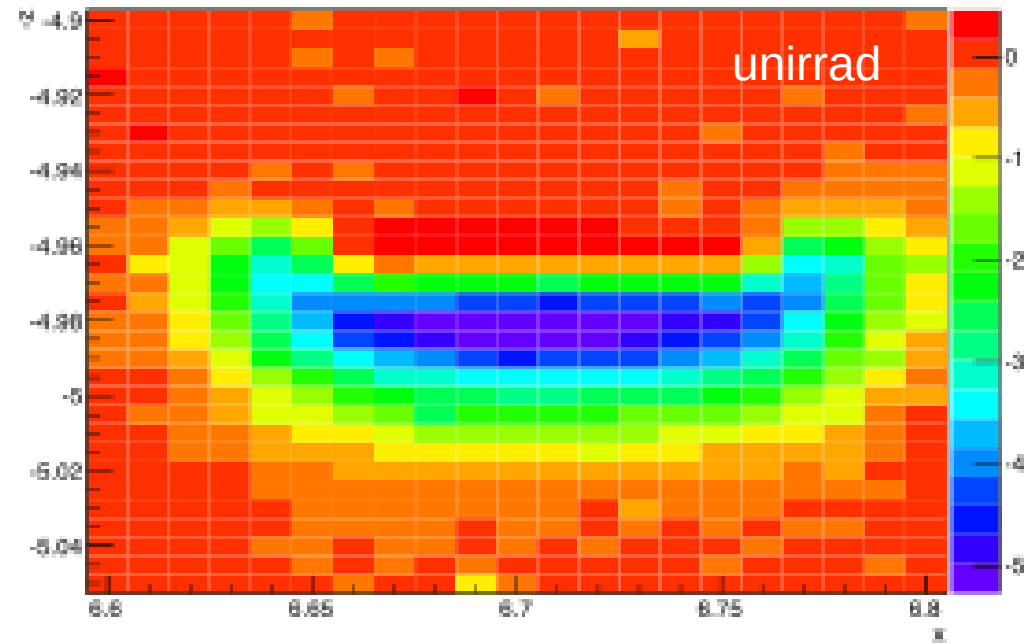
- XZ-scans:
  - **Fast signal** integral as color
  - both at -60V and at room temperature
- Top: unirradiated
- Bottom:  $1e15$  neq/cm<sup>2</sup> n-irrad
- Key observations
  - look very similar
  - no significant reduction
  - post-irrad shows “hotspots”
    - peaks in electric field? Charge amplification?





v3

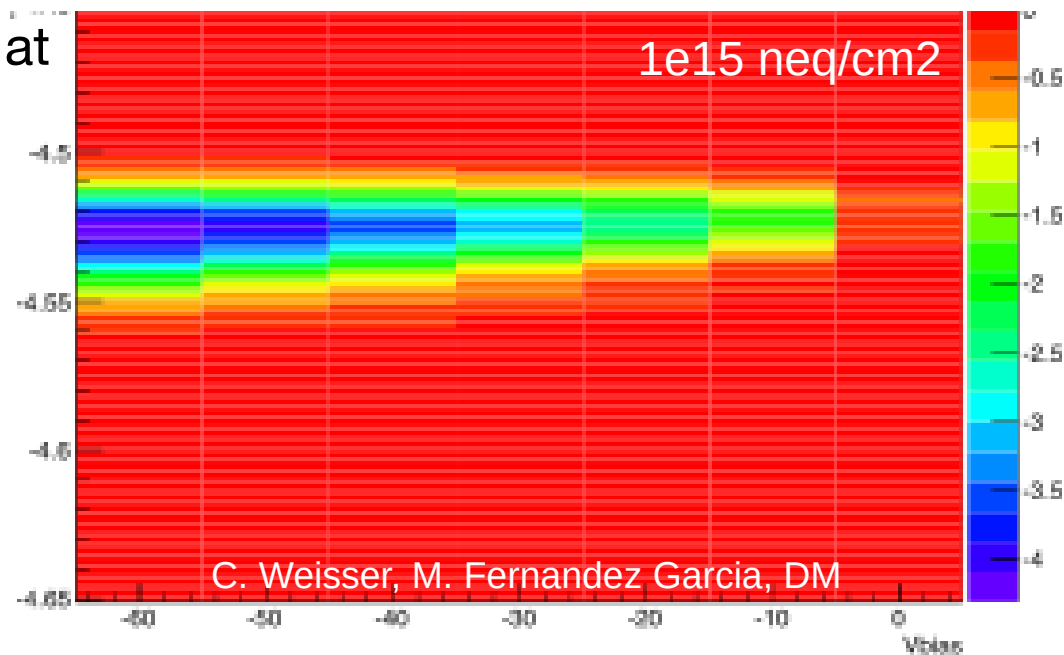
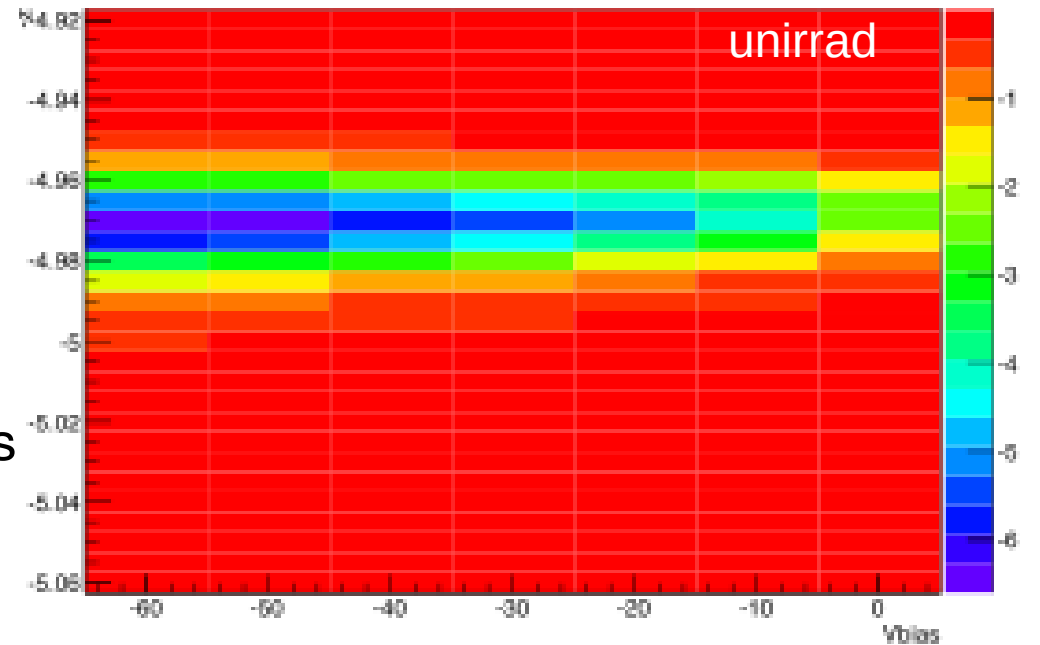
- XZ-scans:
  - **Slow** integral as color
  - both at -60V and at room temperature
- Top: unirradiated
- Bottom:  $1e15$  neq/cm<sup>2</sup> n-irrad
- Key observations
  - extended diffusion zone underneath and laterally of drift zone before irradiation
  - diffusion (almost) gone after irradiation, red spots are undershoots from fast drift signal → artifacts





## v3

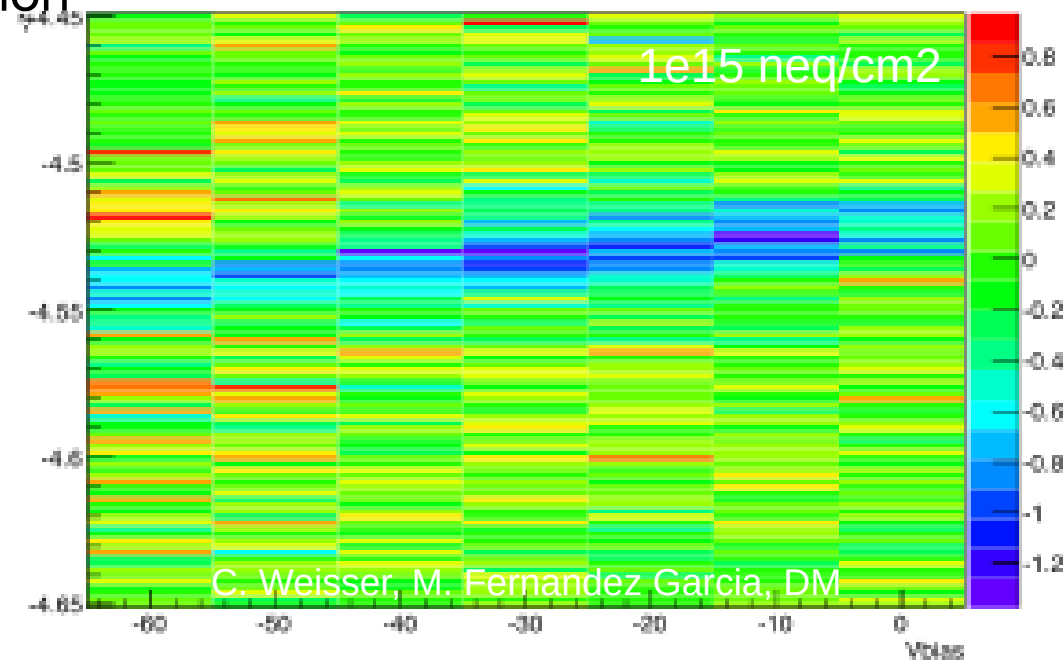
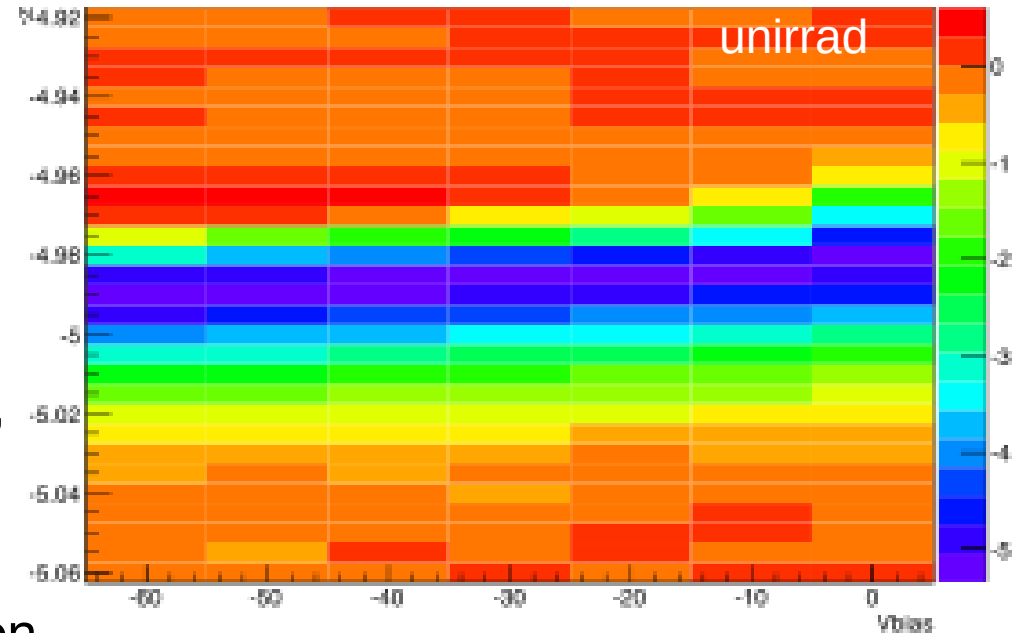
- ZV-scans:
  - **Fast** integral as color
  - between 0V and -60V
- Top: unirradiated
- Bottom:  $1e15$  neq/cm<sup>2</sup> n-irrad
- Key observations
  - zone of large drift signal extends
    - to be convoluted with the  $9\ \mu\text{m}$  sigma of the laser!
    - working on deconvolution
  - after irradiation very little signal at 0V – otherwise very similar...
    - rad-hard?





## v3

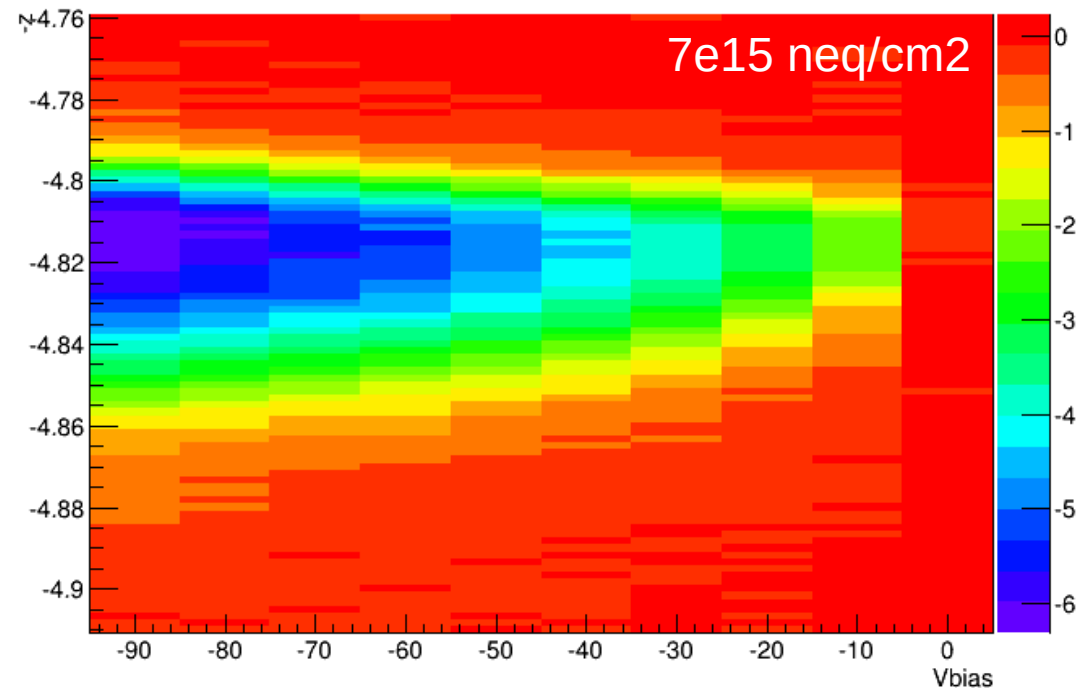
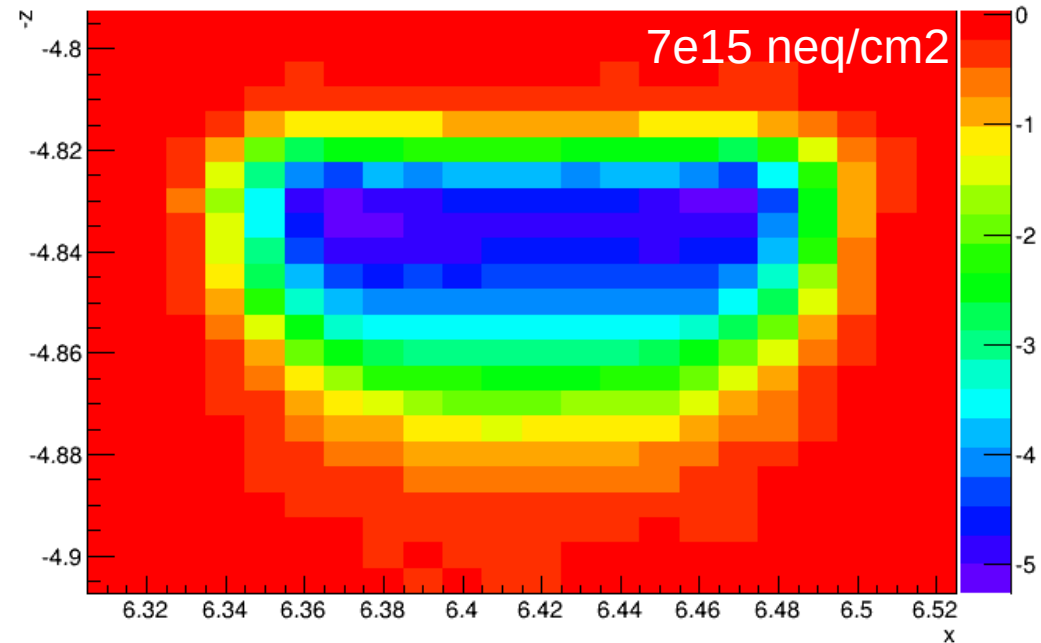
- ZV-scans:
  - **Slow** integral as color
  - between 0V and -60V
- Top: unirradiated
- Bottom:  $1e15$  neq/cm<sup>2</sup> n-irrad
- Key observations
  - diffusion zone is “pushed down” from growing drift zone, but thickness stays ~constant
  - very little diffusion after irradiation (different color code!)





## v3 – higher fluences

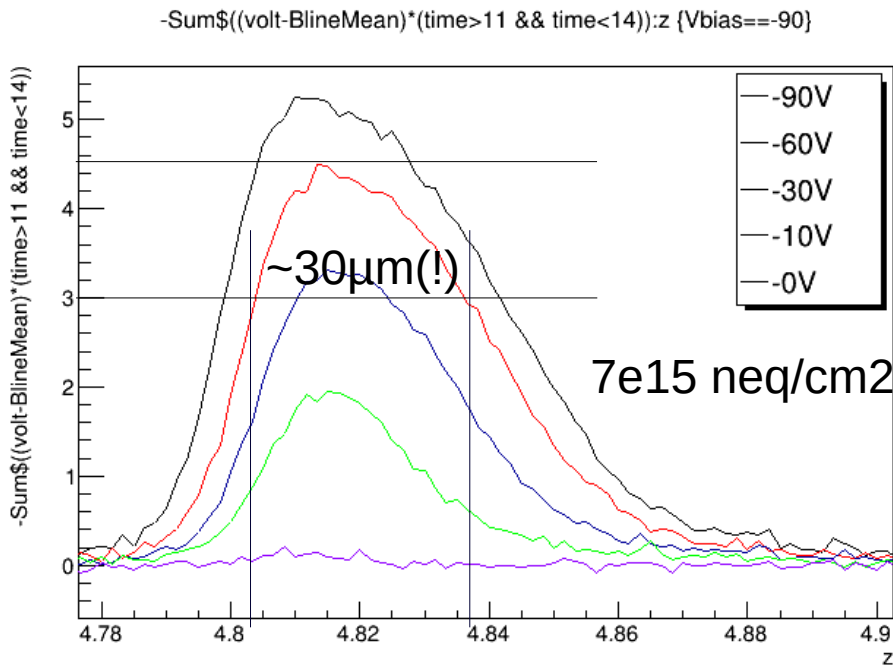
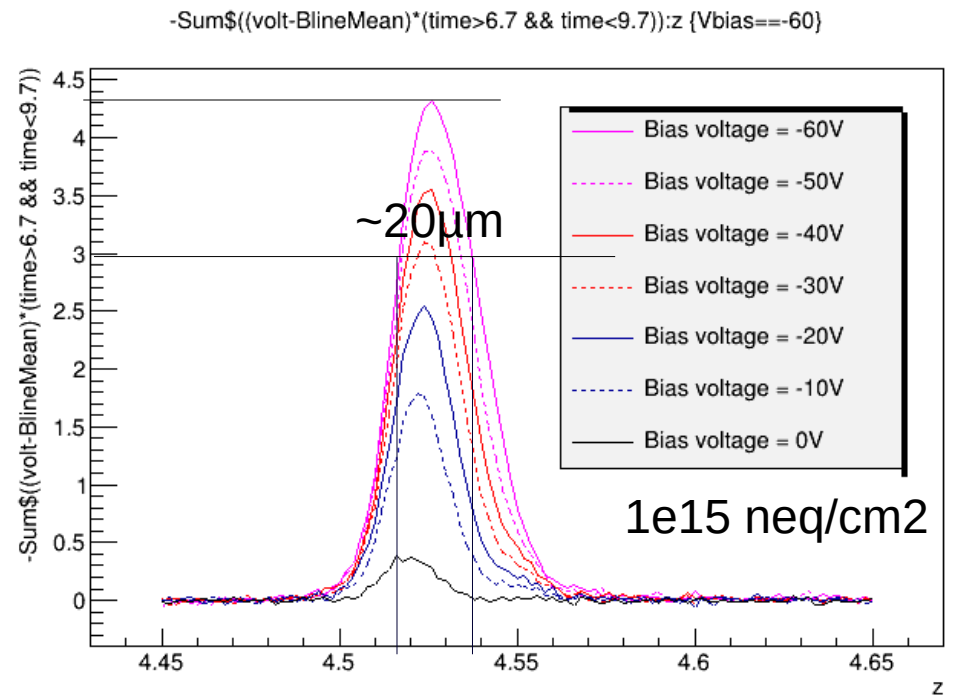
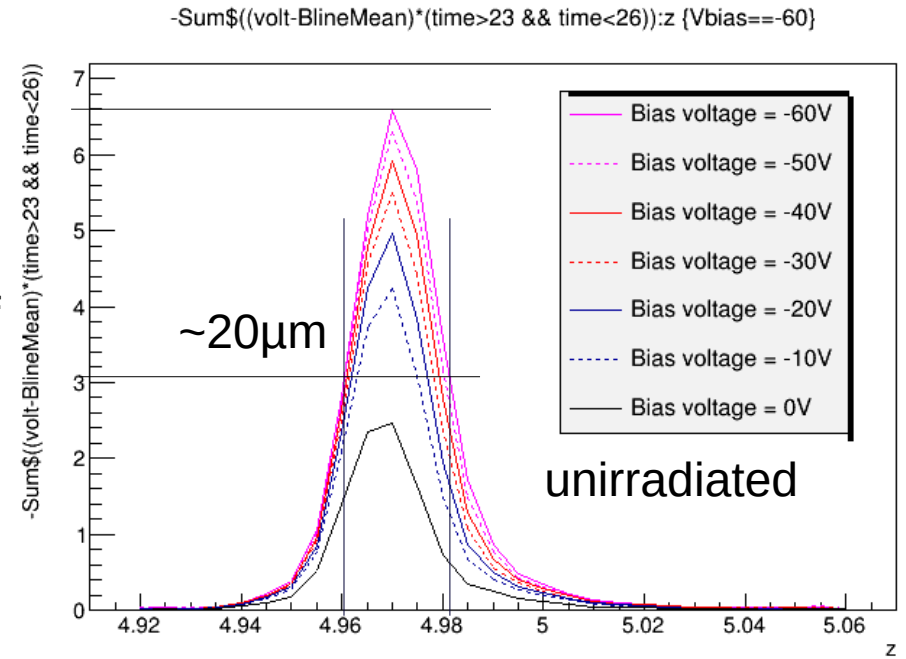
- 1e15 neq/cm2 measurements still done at RT w/o cooling
- 7e15 neq/cm2 only stable until ~25V, then cooling required
  - also reaches “defined” breakdown voltage of ~93V, no change
  - 3ns integral charge ~unchanged wrt to 1e15 neq/cm2 sample
  - peaks in collected charge at edges of implant – high field regions?





## v3 – comparison of regions of fast charge collection

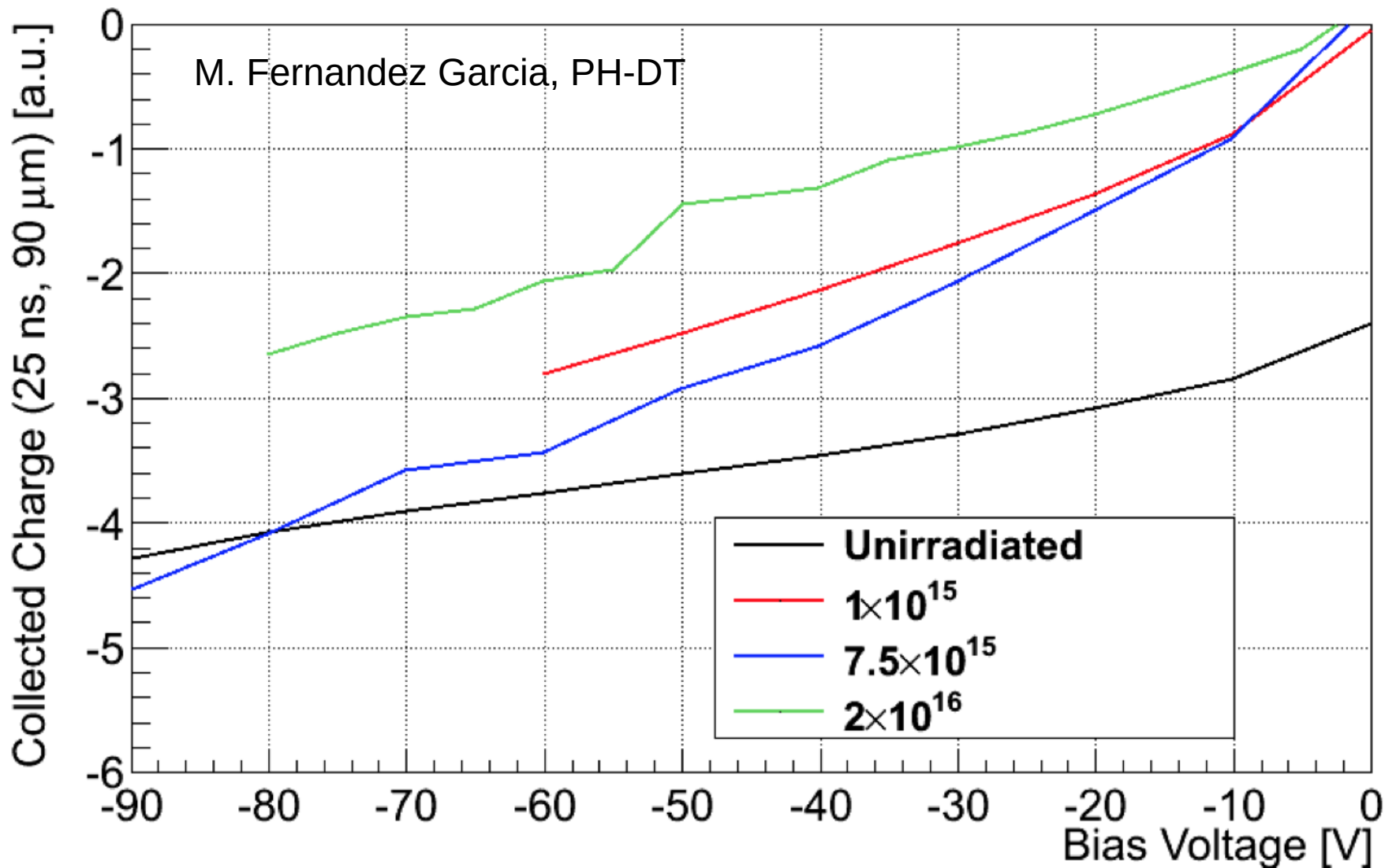
- Measurements still ongoing, **very preliminary**
  - maximum collected charge stays similar to  $1e15$  sample
    - ~expected: short drift distance,  $N_{eff}$  change still insignificant
  - width of charge collection zone larger?
    - also non-symmetric → trapping? E-Field at  $7e15$ ? Acceptor removal!
    - TCAD simulations starting





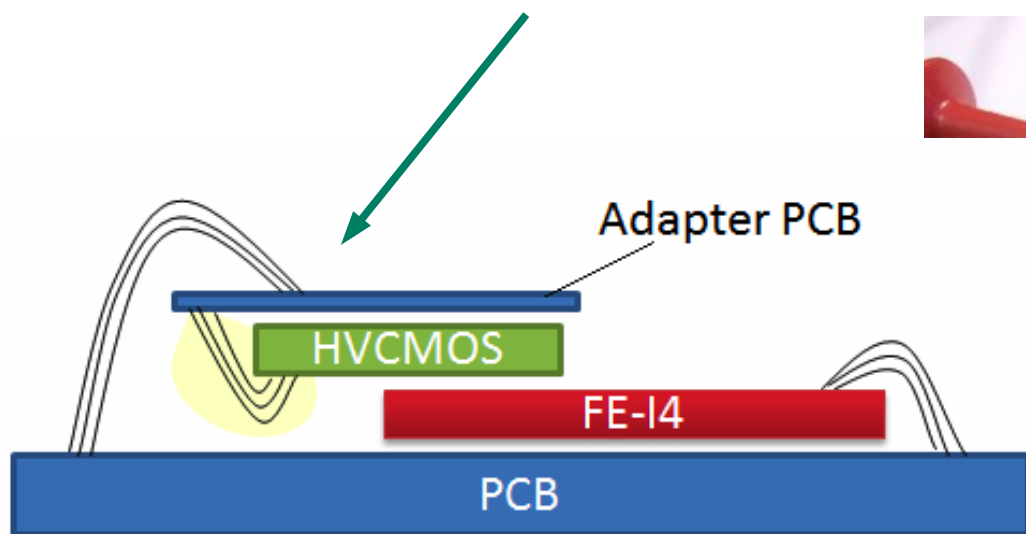
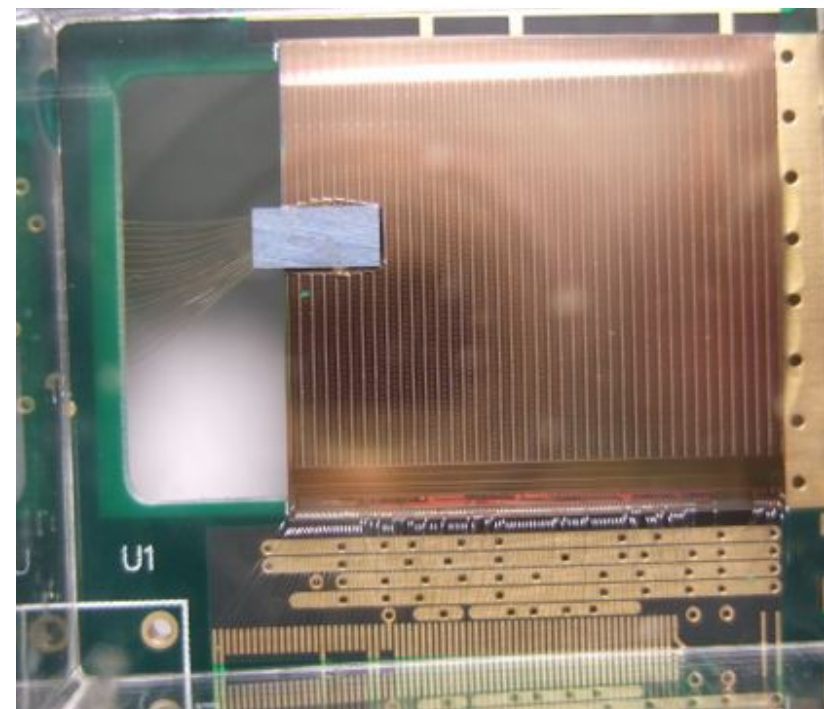
# v3 – comparison of regions of fast charge collection

- Integration over depth within 25ns for different fluences and bias voltages
  - maximum for  $7e15$  – acceptor removal effect? Afterwards trapping kicks in?



## HV2FEI4: Pixel readout

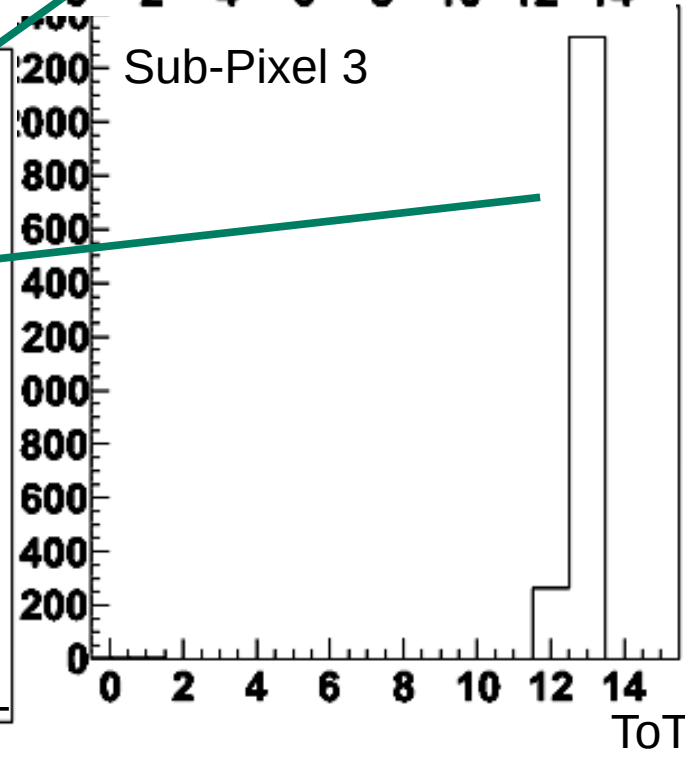
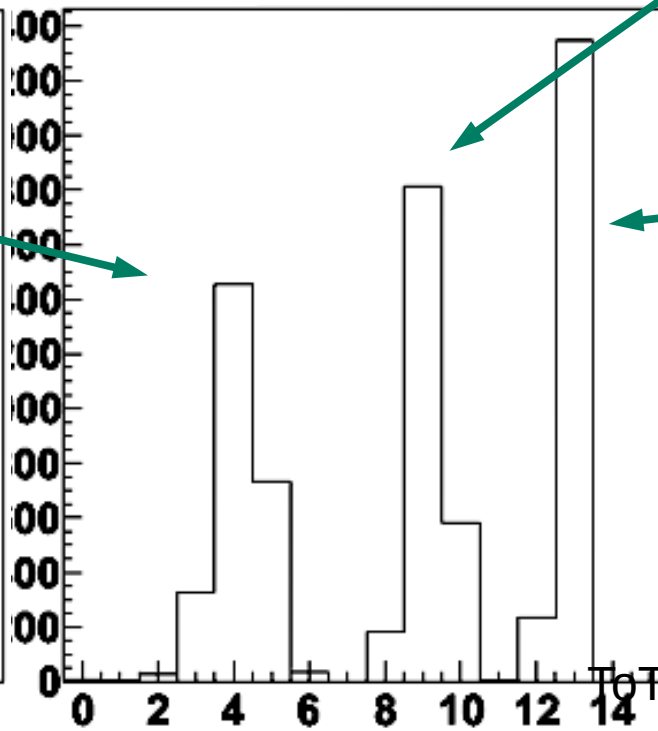
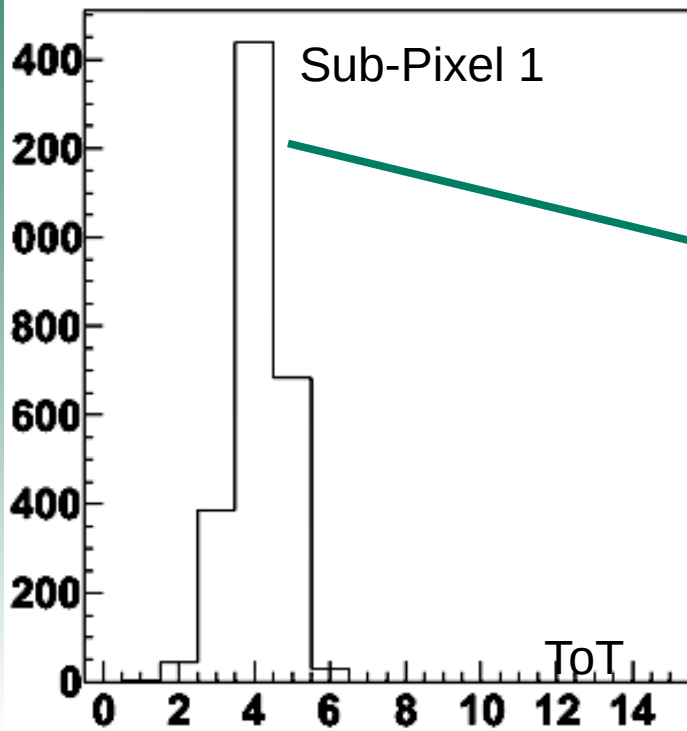
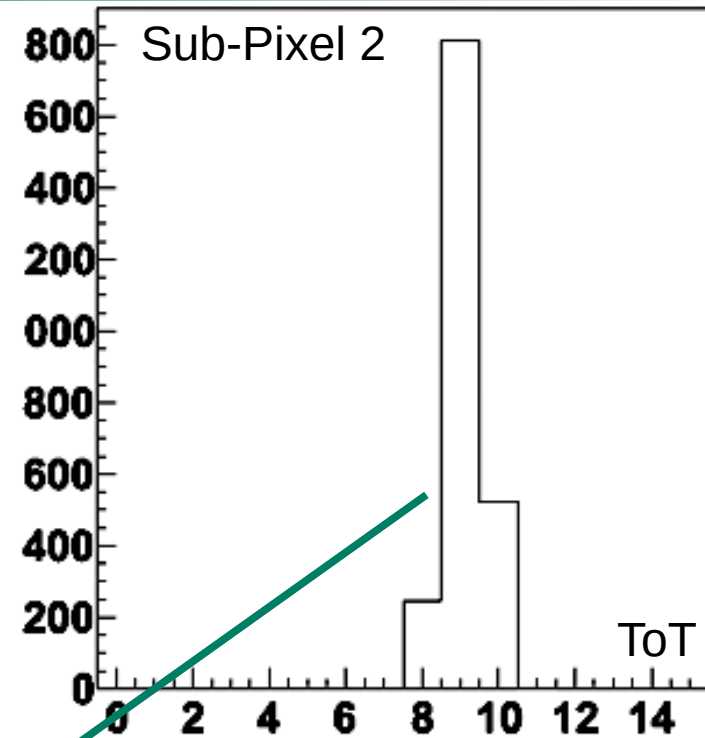
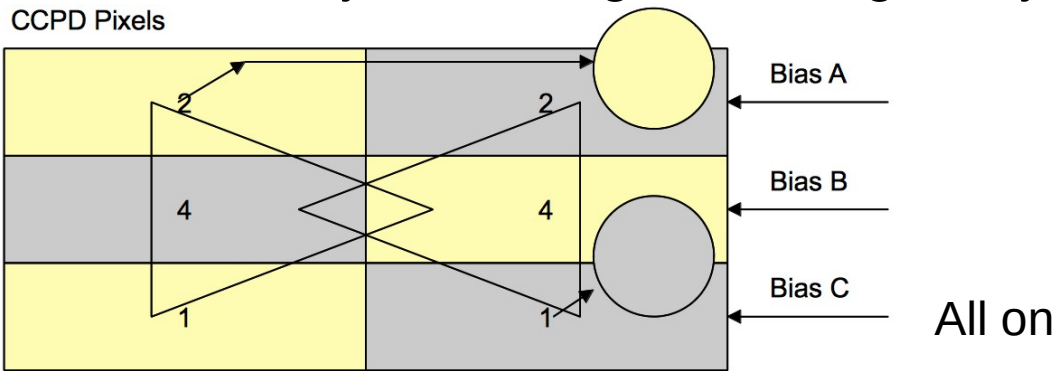
- Several (>20) HV2FEI4s glued to FE-I4 pixel readout chips
  - using pick+place machines, precision requirement estimated to  $<5 \mu\text{m}$  for current bump-pads
- HV2FEI4 wirebonds done through hole in PCB
  - could be bumps or TSVs later
  - unidirectional glues under study
  - adapter PCB in production allowing for single-sided wirebonding after gluing





# HV2FEI4: Pixel readout

- ToT encoding:
  - 3 sub-pixels clearly distinguishable  
→ sub-pixel encoding works!
  - to do: dynamic range matching, array tuning



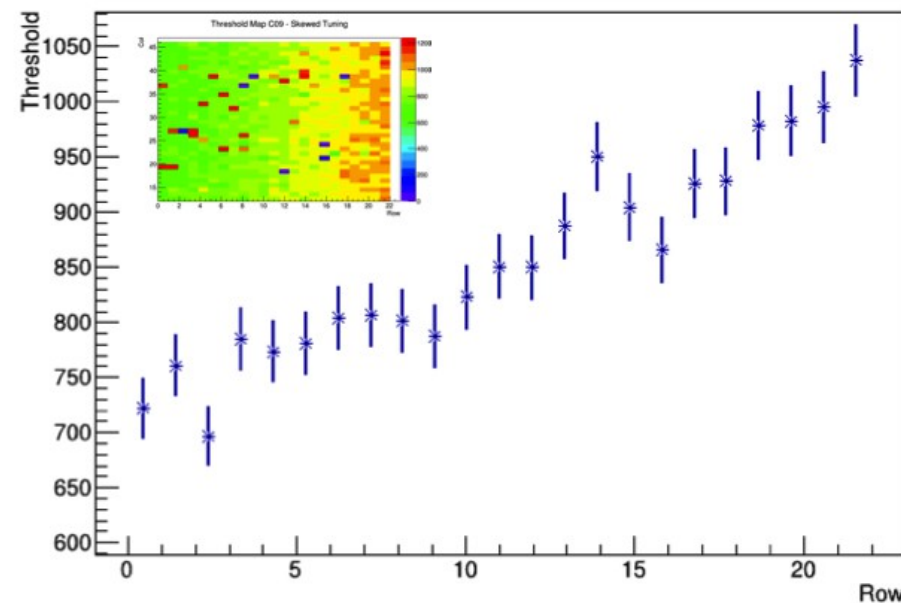
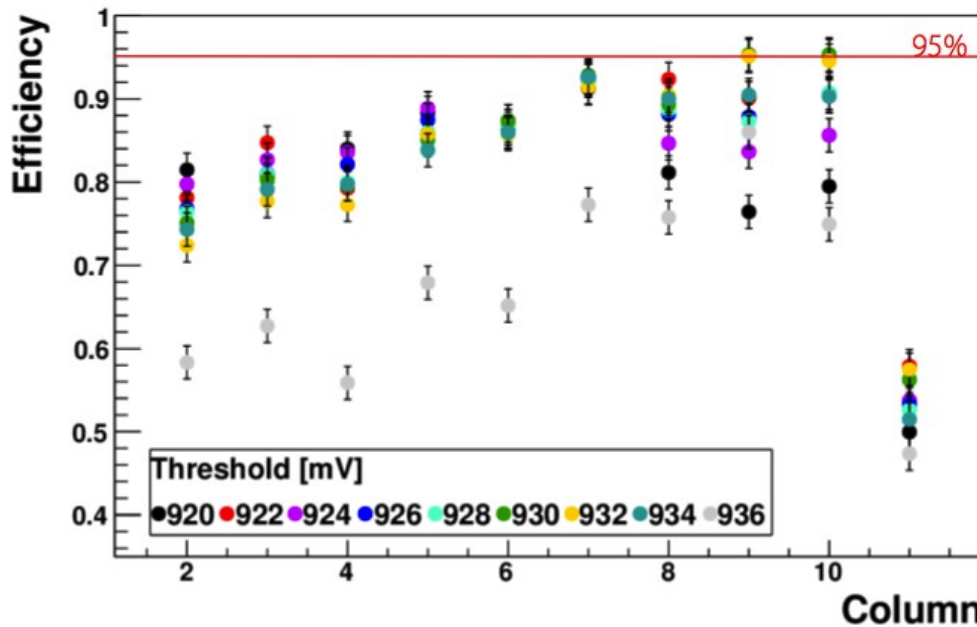


## HV2FEI4: Pixel readout in testbeam

- First data taken at 2013 DESY testbeams
  - unirradiated and reactor neutron (JSI) irradiated devices:  $1e15$  neq/cm<sup>2</sup>
  - complex geometry complicates alignment
  - non-optimal tunings lead to less efficiency
    - tuning procedures quite fresh at time of testbeam
    - unintentional “skewed” tuning:  $\sim 700$ - $1000$  e-
    - resulting efficiency unirradiated:  $\sim 95$ - $80\%$



Threshold vs. Row (FEI4 column) - C09 - Skewed tuning

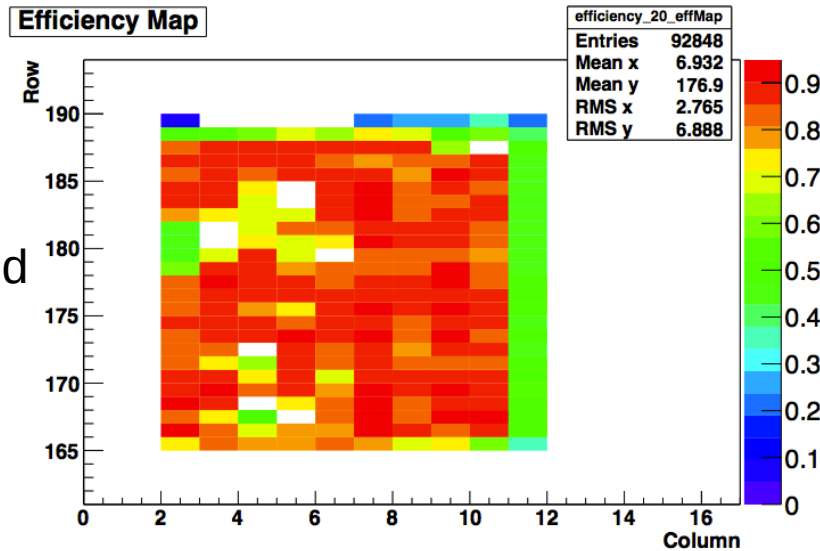




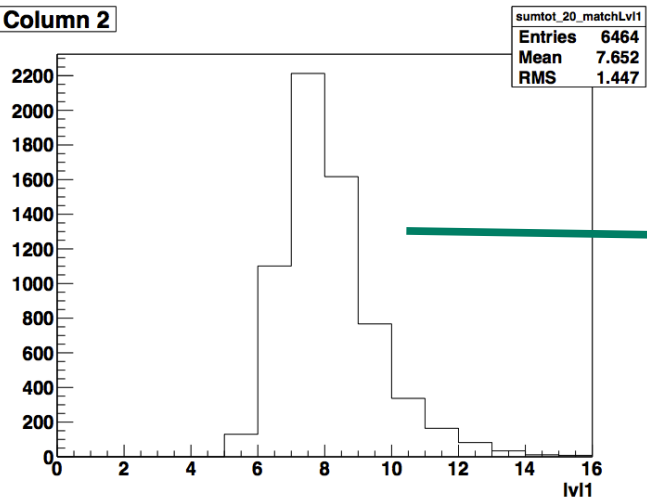
## HV2FEI4: Pixel readout in testbeam

- First data taken at 2013 DESY testbeams
  - time-walk depending on threshold – low threshold → better timing

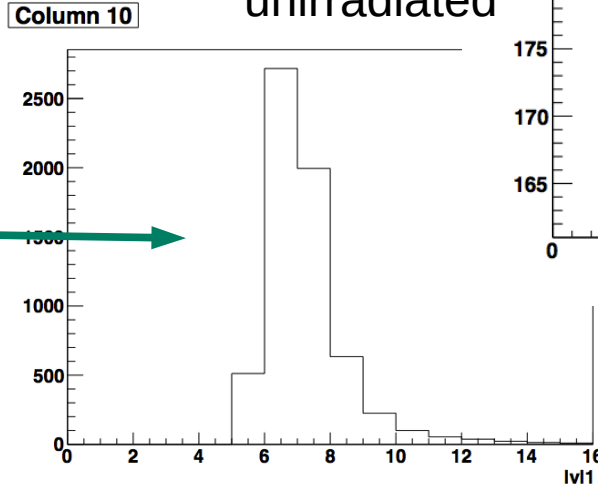
Efficiency Map



Column 2



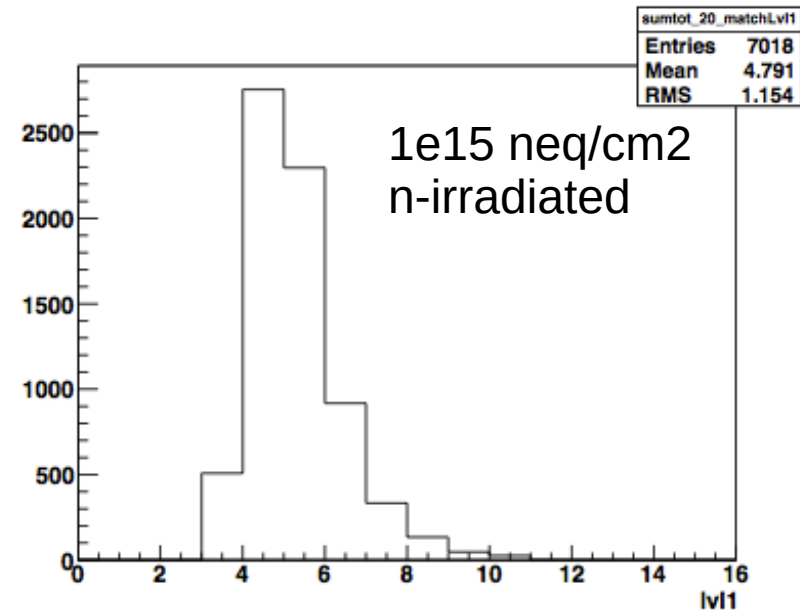
Column 10



- irradiated sample shows strong HV-dependence of efficiency, timing similar

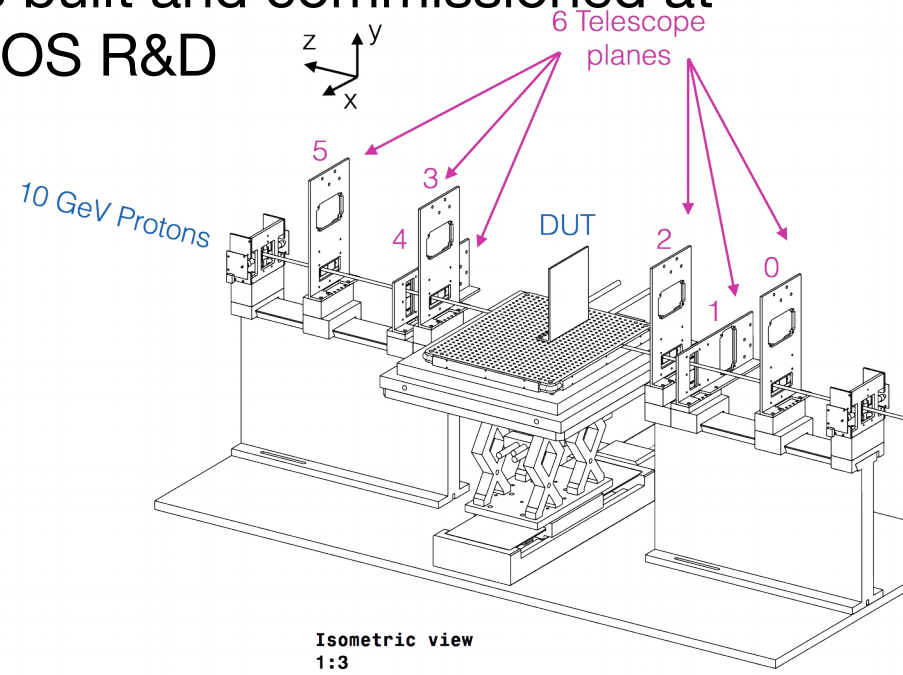
Runs	HV [V]	Trigger	Tracks	Eff
230-232	-57.6	566k	6011	62.9%
224-225	-48.0	517k	10993	54.8%
233-235	-38.4	551k	9783	64.0%
236-238	-28.8	543k	437	51.7%
239-241	-19.2	543k	2590	38.2%
242-244	-9.6	587k	6804	28.2%
245-247	0.0	553k	8969	12.5%

sumtot\_20\_matchLv1

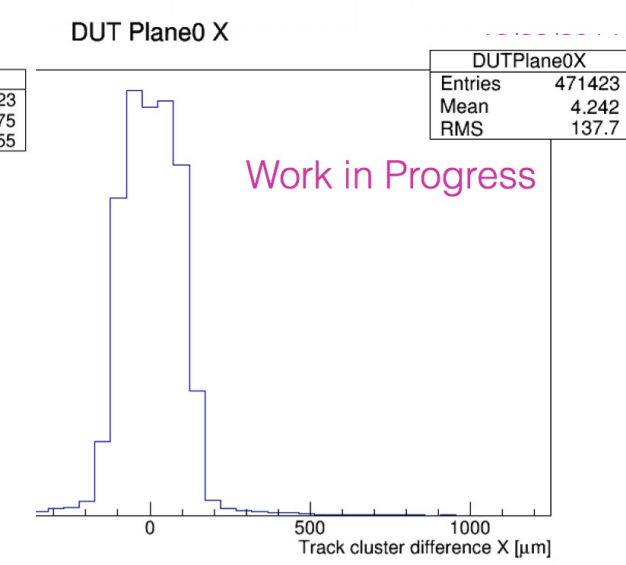
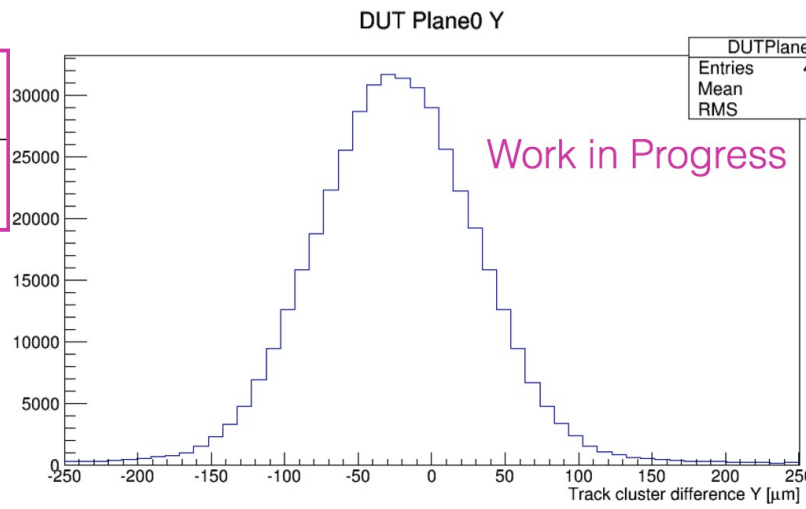
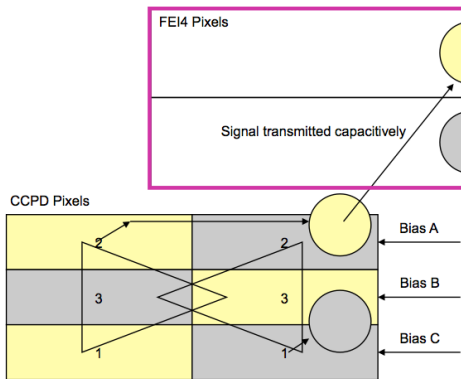


## New tuning implemented, new telescope 2014

- Due to some issues with desynchronisation and the very small DUT area, a new FE-I4-based telescope was built and commissioned at CERN PS with special focus on HV-CMOS R&D
- Low energy beam (10 GeV) in combination with large DUT distance (~25 cm) lead to rather large residuals/pointing uncertainty
  - subsequent run at SPS
- No sub-pixel encoding this time, merged pixels to avoid ambiguities



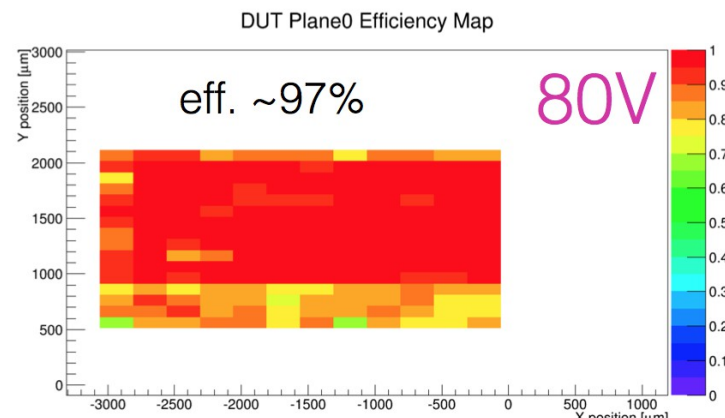
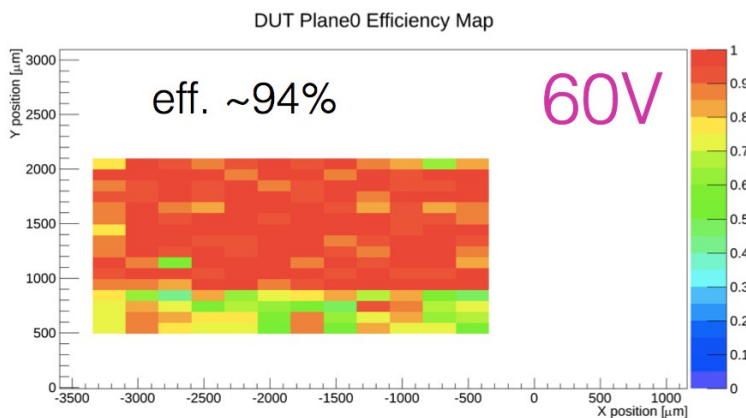
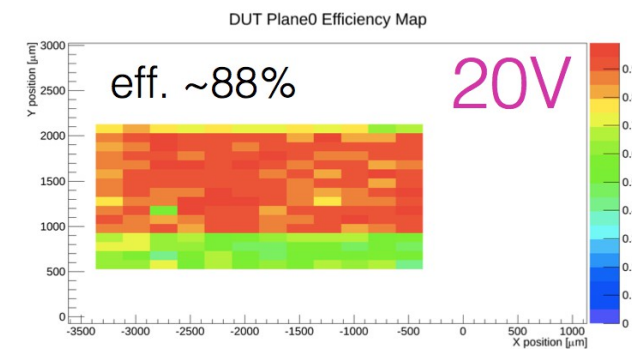
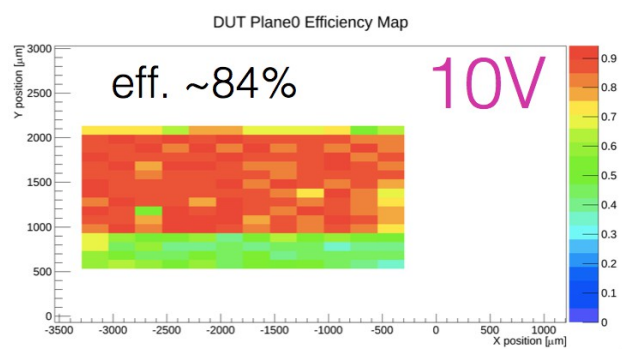
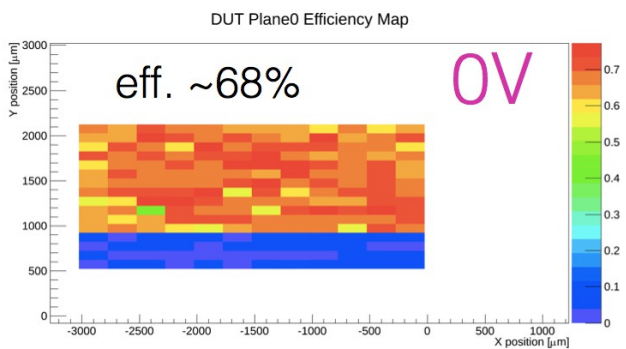
### Pixels of 100 x 250 Unit cell





# New tuning implemented, new telescope 2014

- New noise tuning was implemented aiming to tune every pixel as low as noise occupancy allows
  - works in principle, matrix effects still to be studied
- With unirradiated sample sees clear effect of bias voltage on efficiency
  - low efficiency region at bottom are “rad-hard” pixels with higher threshold setting → understood
  - need to understand where/if ~3% efficiency are lost: multiple scattering, interpixel field gaps, ...

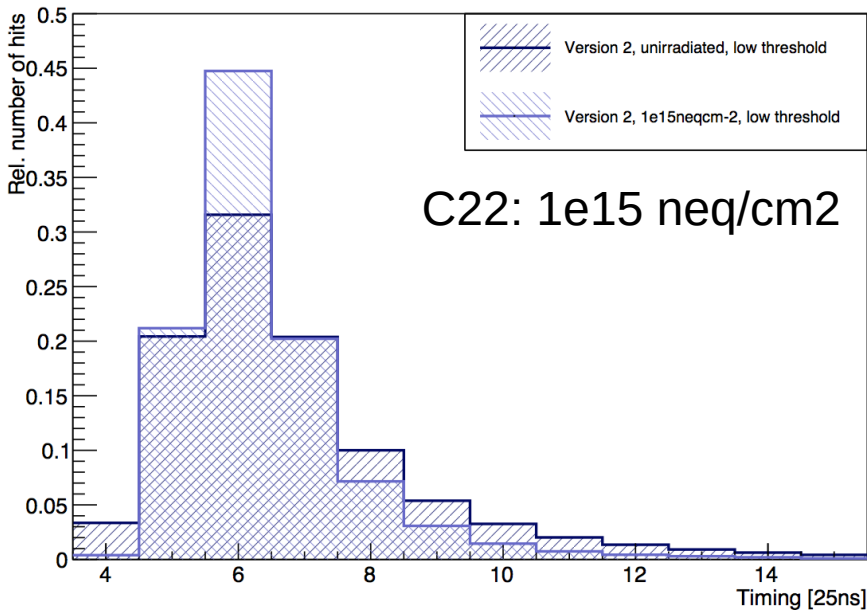
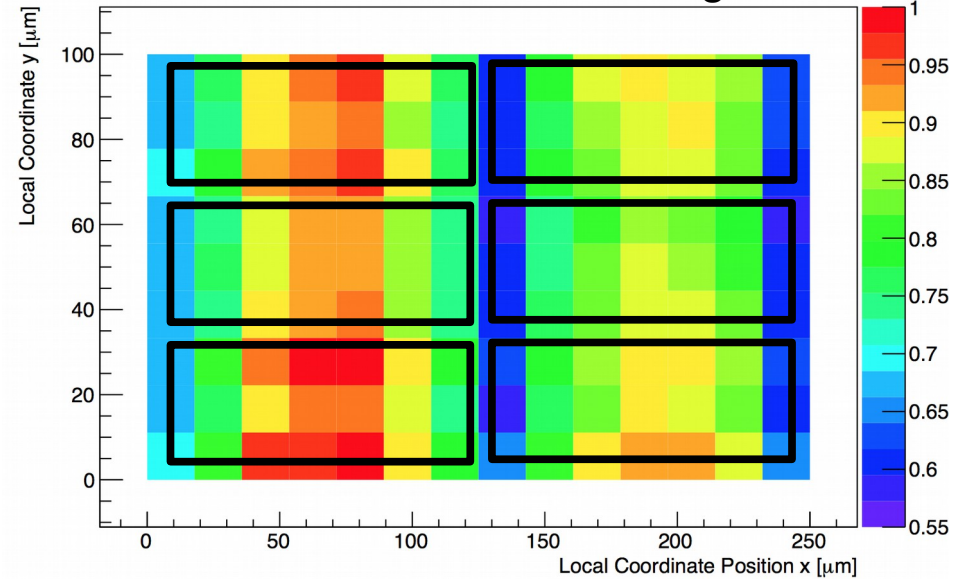




## A preliminary look at SPS testbeam data

C19 (unirrad. v2)  
at high threshold

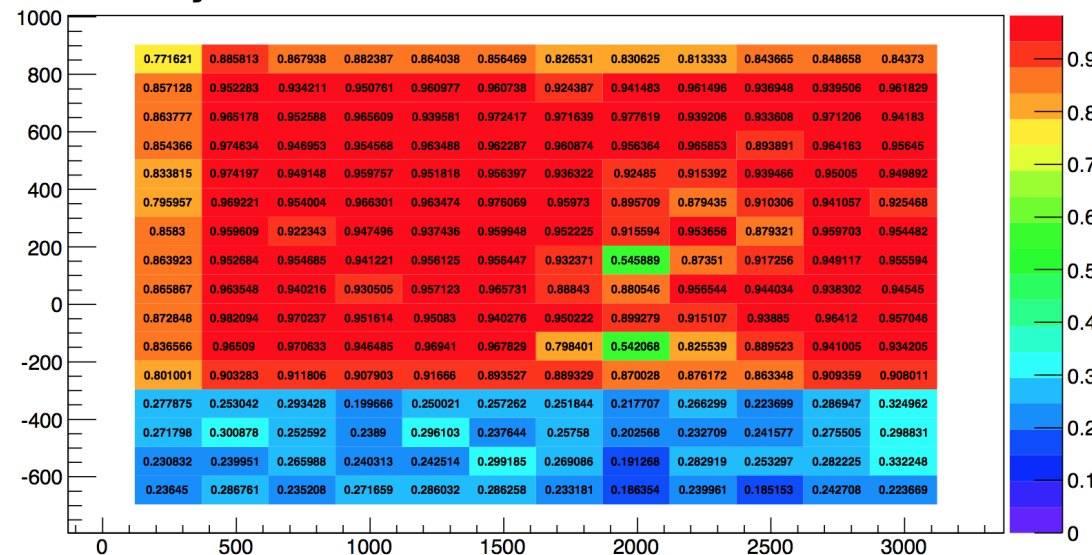
- Residuals at SPS much nicer – less multiple scattering
  - efficiency lost in between sub-pixel boundaries (gap for guard rings)
  - gap can be optimised/minimised
- Irradiated assemblies show comparable efficiencies
  - 1e15 neq/cm2: mean ~95%, indiv. pixels up to 98% (noise tuning)
  - timing improving: 85% @ 3BC



C22: 1e15 neq/cm2

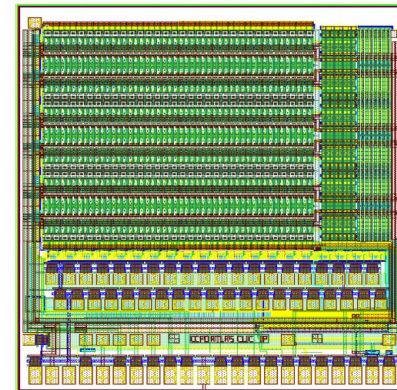
Preliminary

DUT Plane0 Efficiency Map

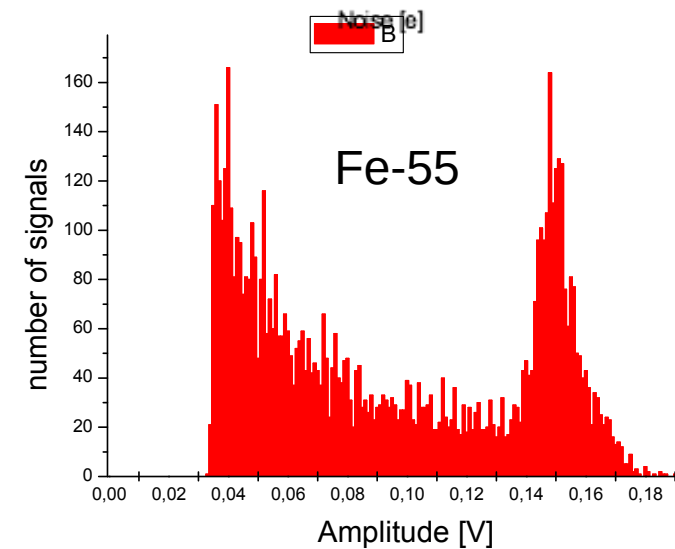
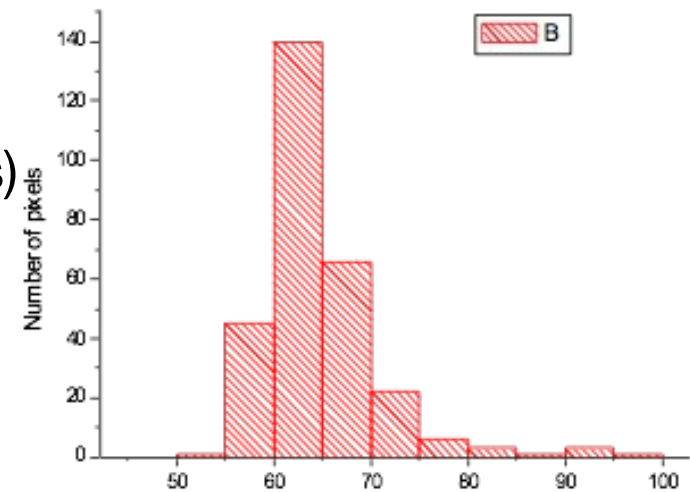
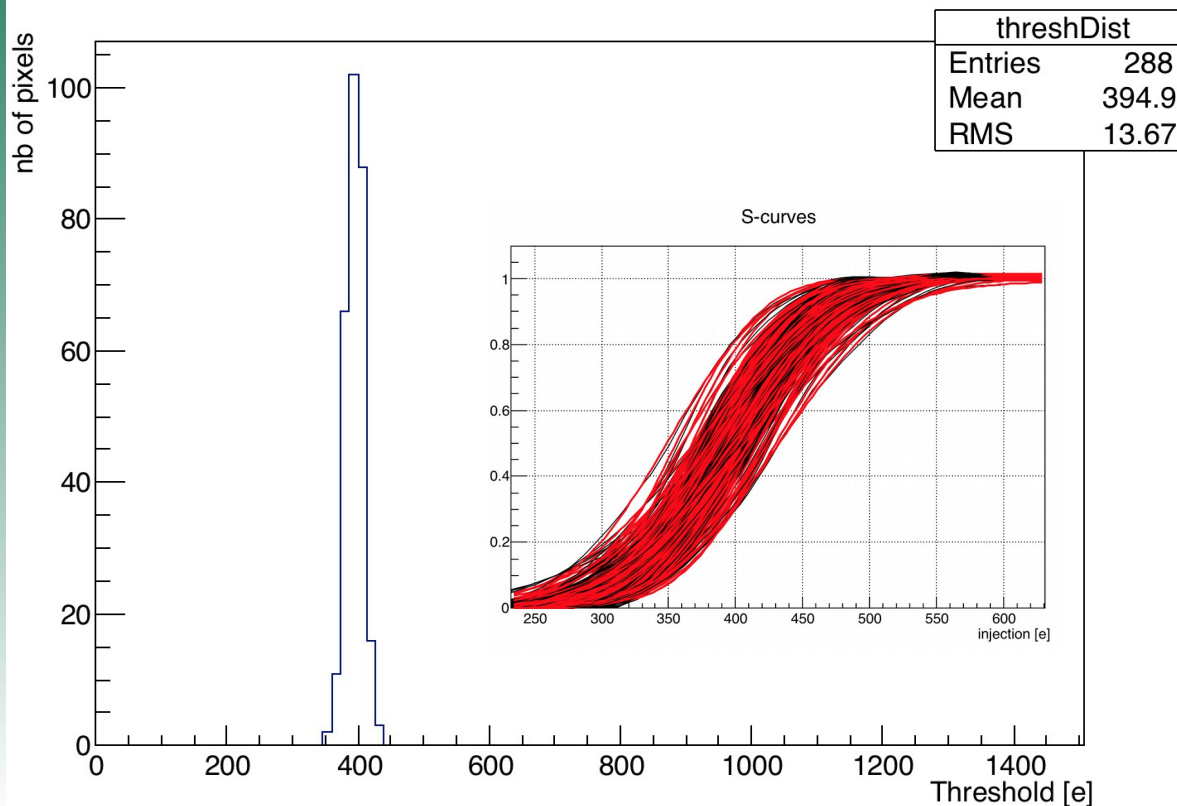


## A glimpse on the next pixel prototype

- H18\_v4
  - focused on ATLAS-pixel readout, several noise improvements, segmented pixels, analogue pixels (25x250 $\mu$ m), pulse-width encoding of sub-pixel address promising better ToT encoding
  - tunings to 300-400 electrons possible
  - First preliminary testbeam results comparable, >95% efficiency after irradiation (eff. lost at gaps)

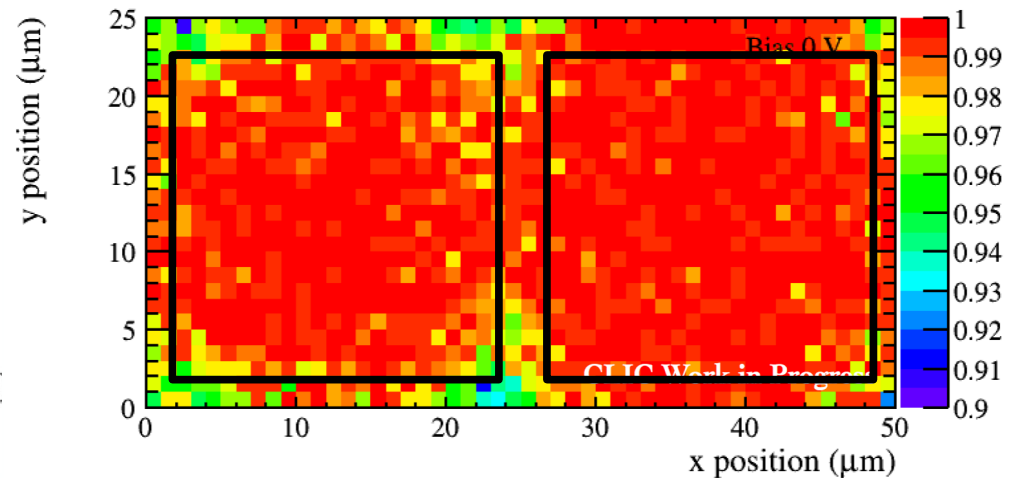
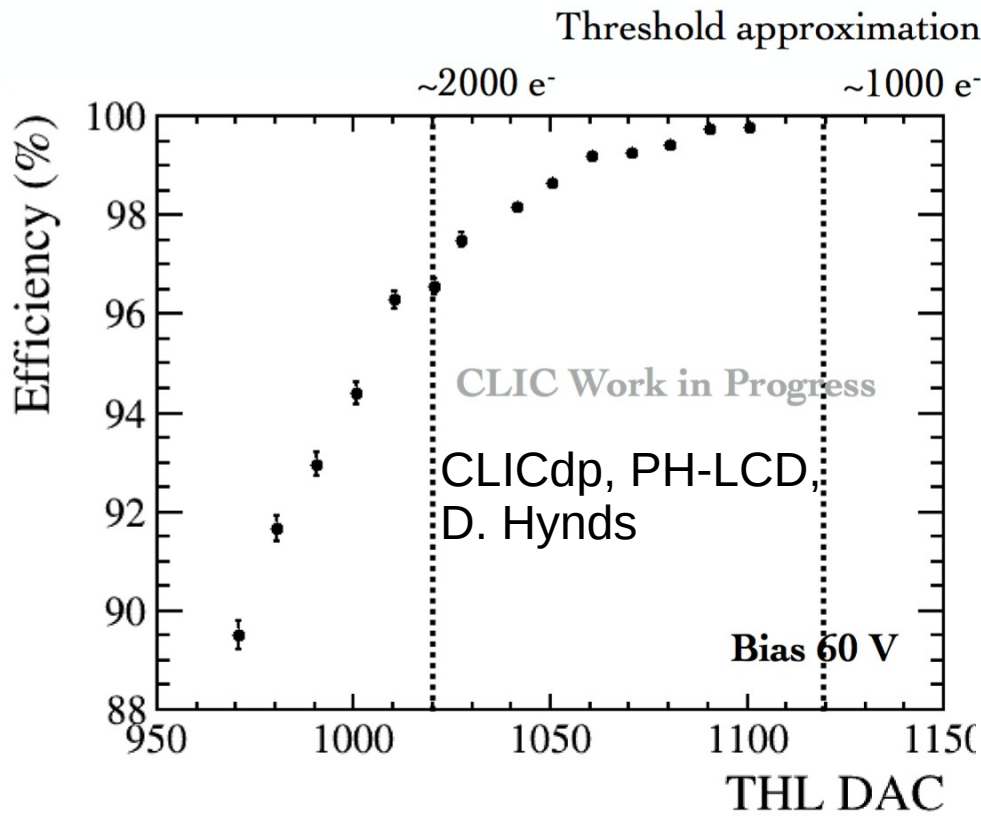
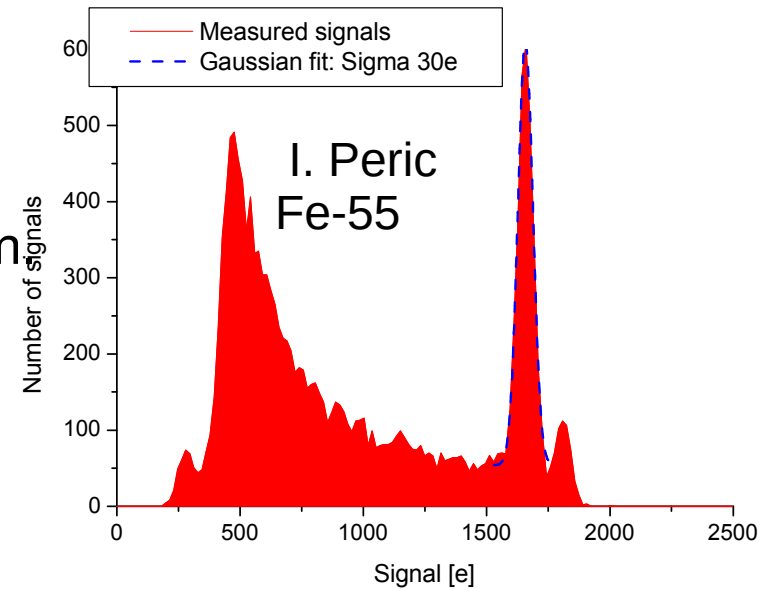


Threshold distribution



## A glimpse beyond ATLAS

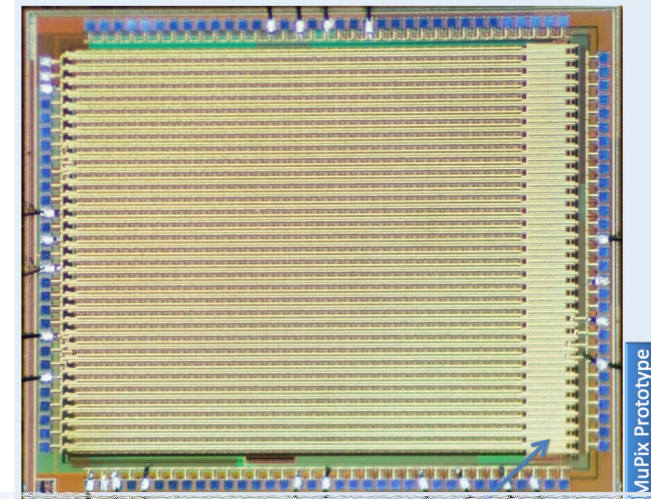
- H18\_v3: CLIC usage with 25x25  $\mu\text{m}$  purely analogue pixels
  - no digital activity in pixels, good noise performance
  - has been implemented in H18\_v4 for ATLAS-size pixels as well, analysis underway
  - efficiency  $\sim 99.7\%$  at  $\sim 1000 e^-$  threshold
  - 3  $\mu\text{m}$  gaps, efficiency loss only in corners due to charge sharing



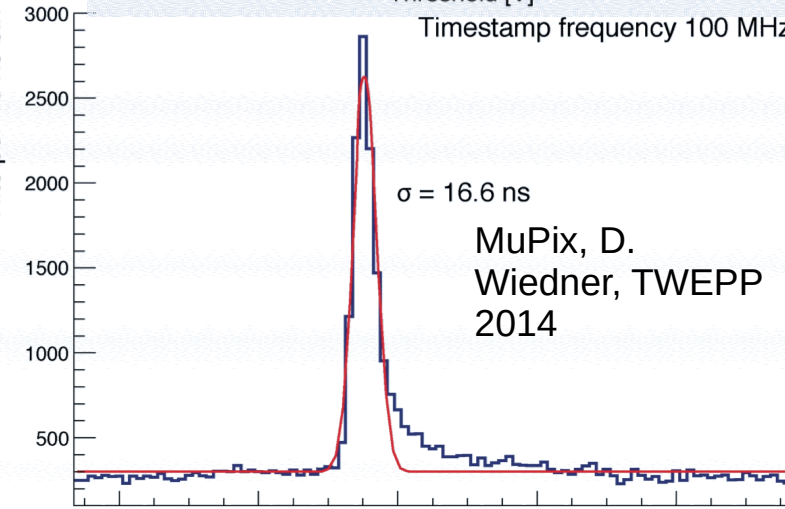
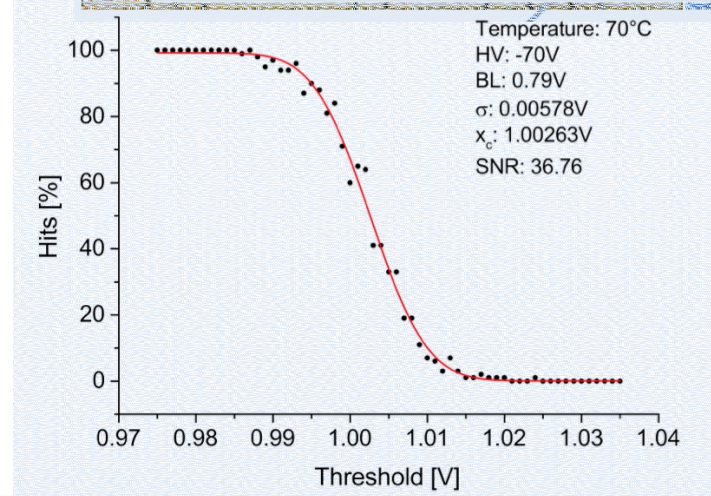
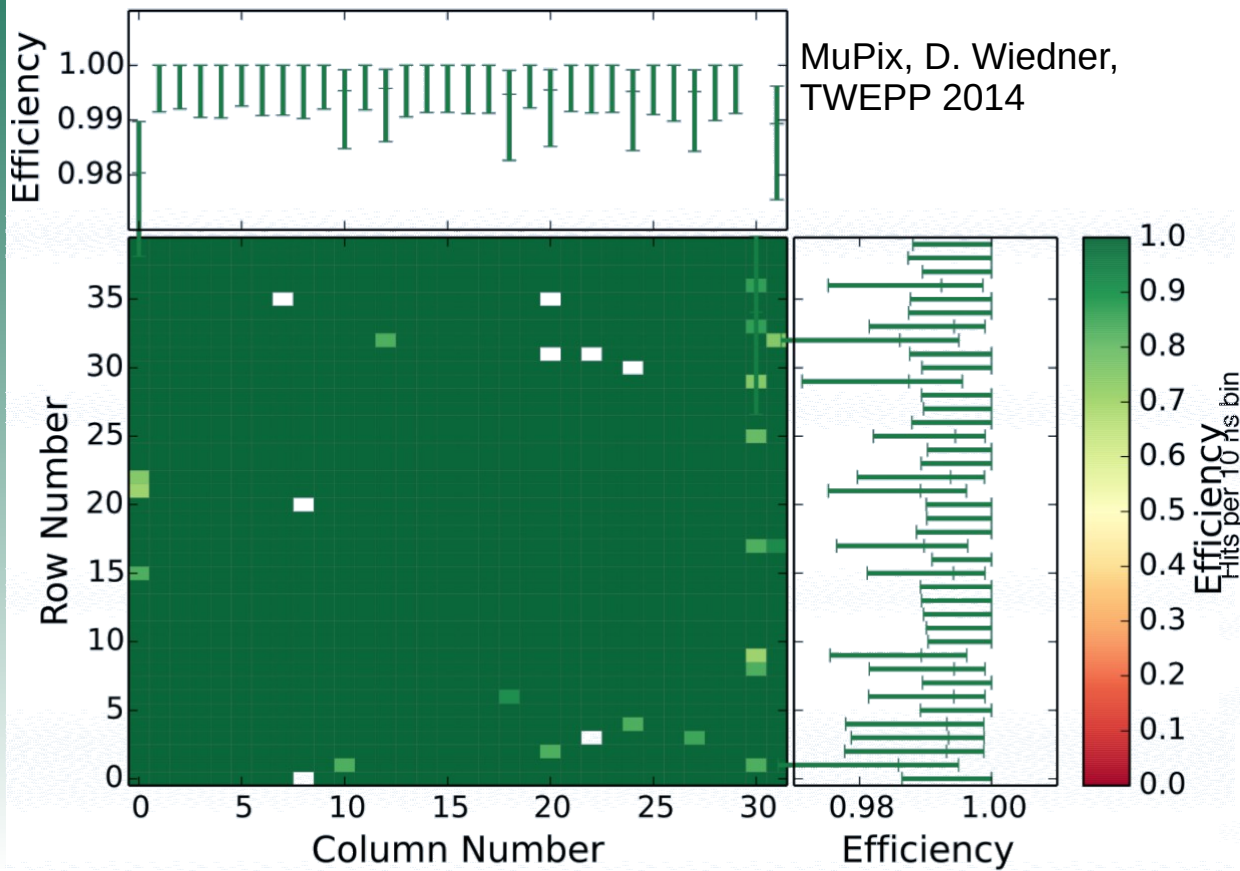


## A glimpse beyond ATLAS

- mu3e experiment at PSI: MuPix chip
  - monolithic, only analogue pixel cell amplifier
  - 80  $\mu\text{m}$  x 92  $\mu\text{m}$  pixel size
  - >99% efficiency measured in test beam
  - timing looks also promising
  - only “drawback”: triggerless operation...



MuPix Prototype

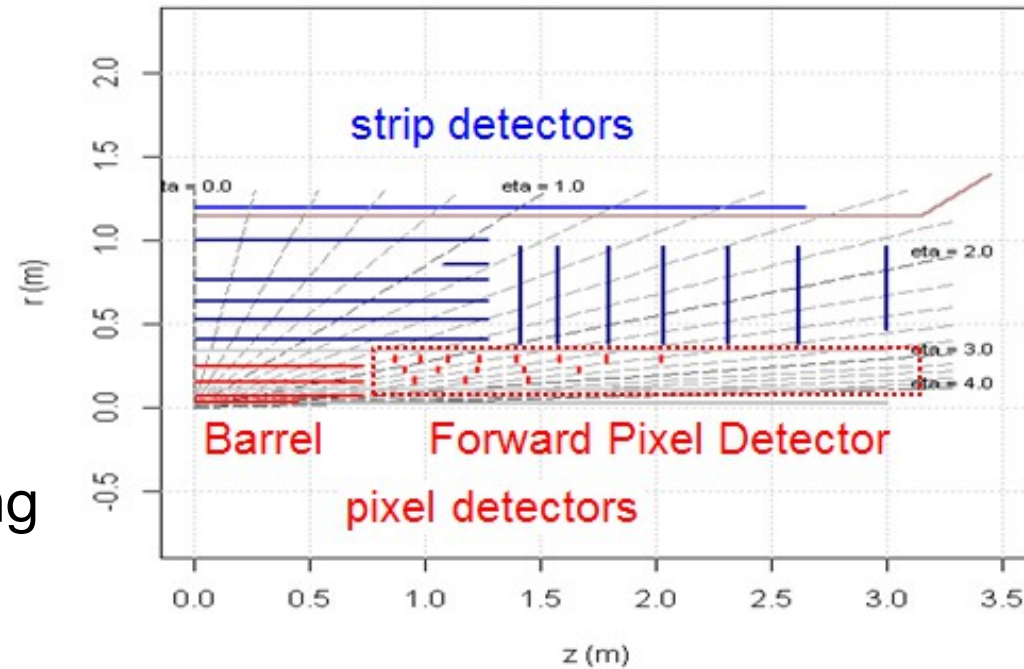






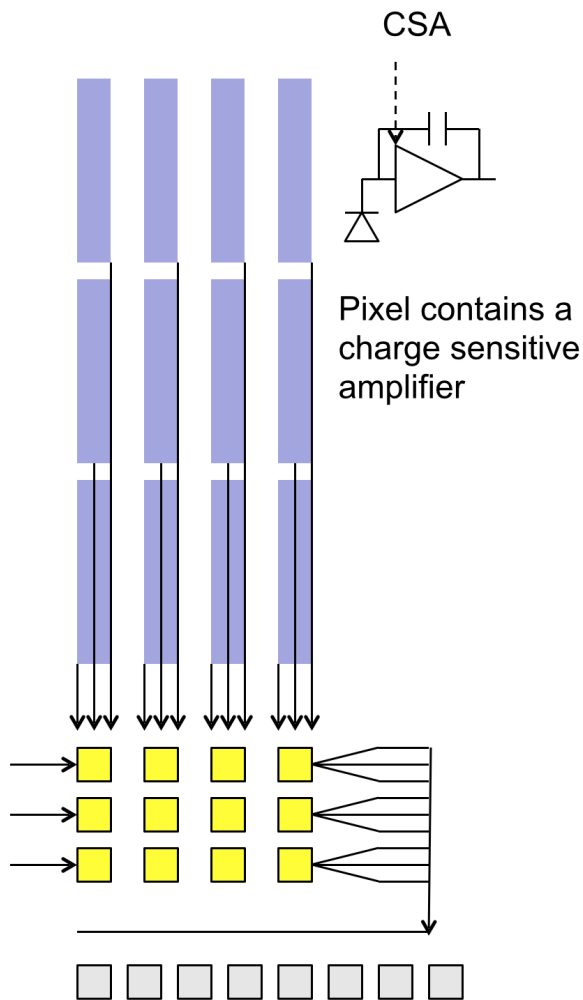
## A glimpse beyond pixels: the “strip” region

- Very large area ( $\sim 200 \text{ m}^2$  of silicon)
  - cost very important
- Radiation damage limited
  - $< 1 \text{e}15 \text{ neq/cm}^2$
  - $< 60 \text{ MRad}$
- Occupancy rather low, but trigger and readout constraints challenging
- Idea: “Almost HV-MAPS”
  - utilise existing trigger handling, pipeline and high-speed communication as implemented in ABCN13 chip (or successors)
  - replace analogue ROC components by in-sensor circuits
    - preamplifier in pixel cell
    - discriminator in periphery  $\rightarrow$  LePix/MuPix concept, less noise/crosstalk
  - “abuse” ABCN pipeline: instead of hit strip pattern store pixel addresses
    - “digital encoding” rather than analogue encoding of hit along strip
- ATLAS started a demonstrator programme with the goal of providing full-size prototype modules by the end of 2015
  - significant activity from “strip” institutes, HV/HR-CMOS explored

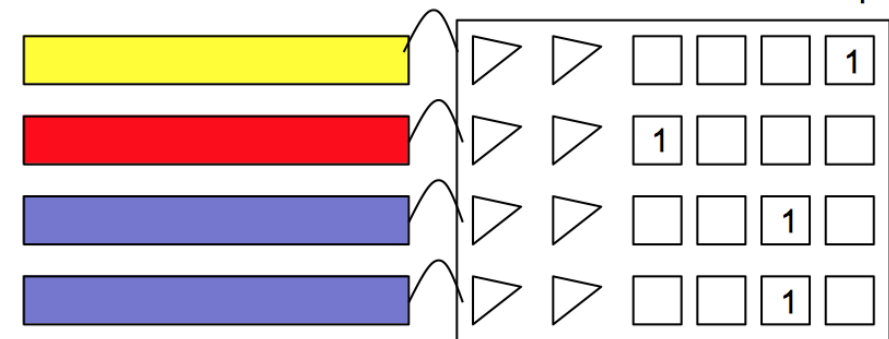


## HVStrip chip concept

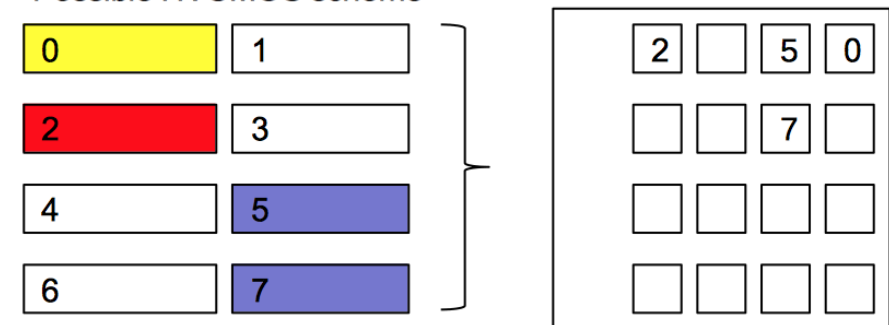
- Each pixel contains a preamplifier with dedicated trace to the periphery
- Periphery contains
  - CFD-like timewalk-compensating discriminator
  - priority encoder to realise a lossy constant latency readout scheme adapted to the current strip readout architecture



Present scheme



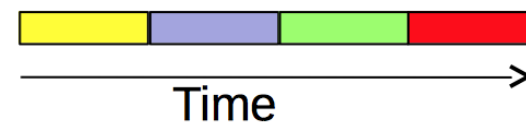
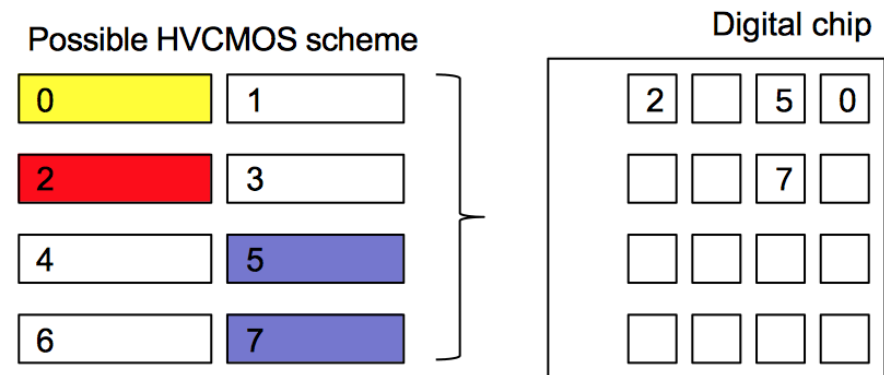
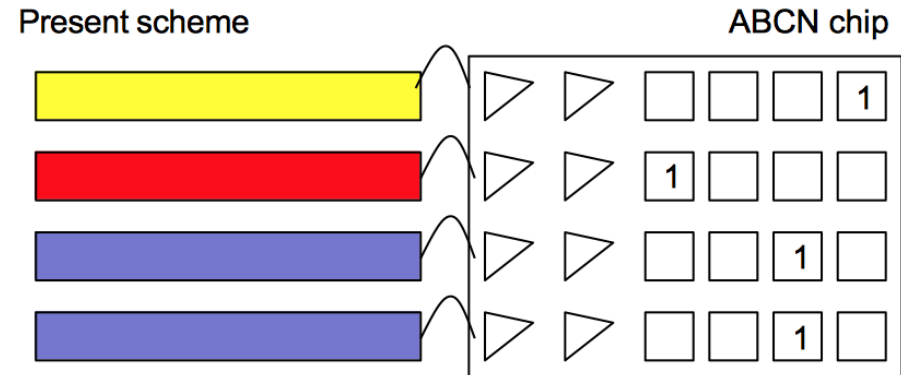
Possible HVCMOS scheme



Time

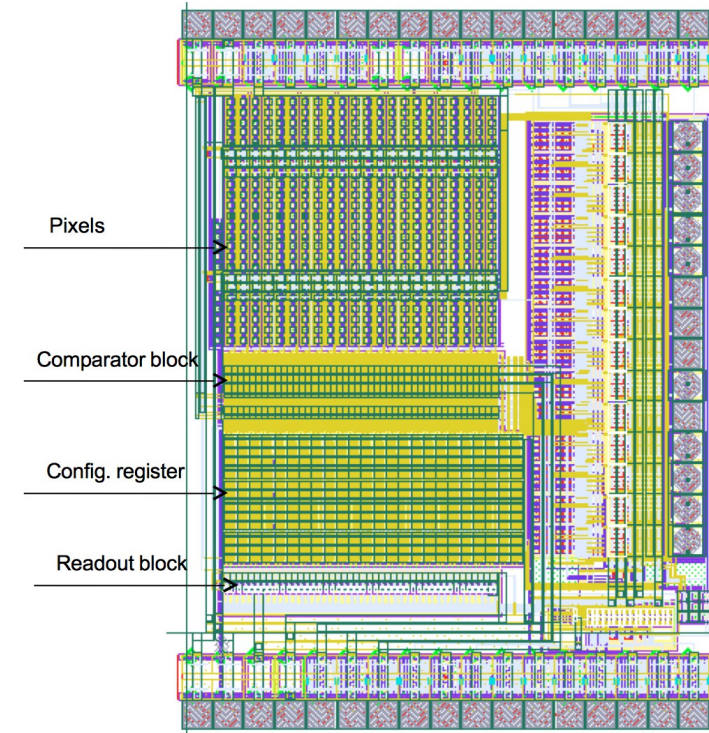
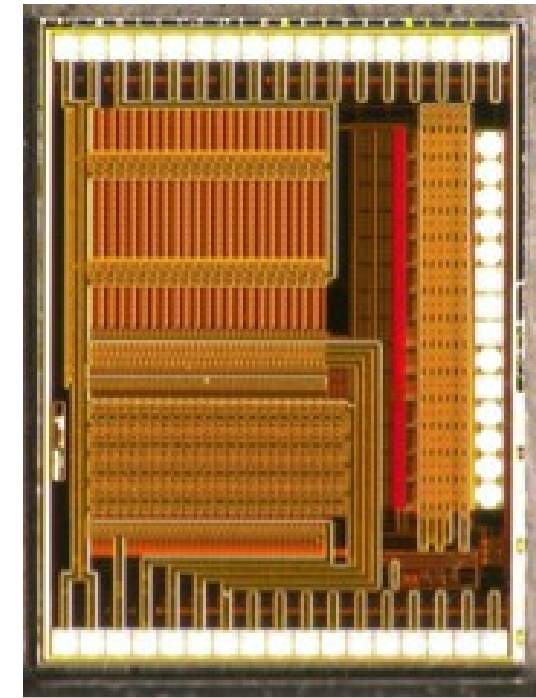
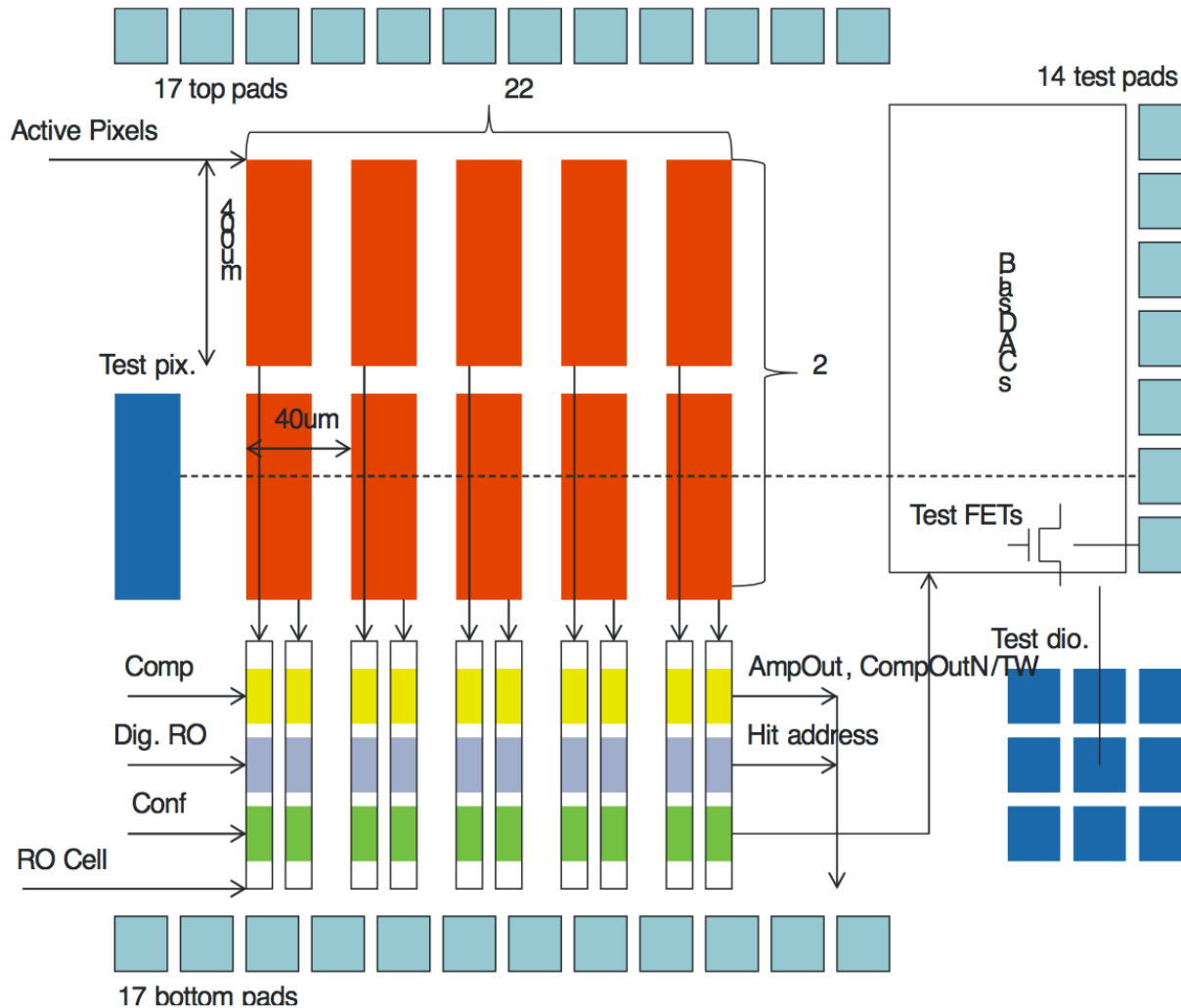
## HVStrip chip concept

- Each pixel contains a preamplifier with dedicated trace to the periphery
- Periphery contains
  - CFD-like timewalk-compensating discriminator
  - priority encoder to realise a lossy constant latency readout scheme adapted to the current strip readout architecture
- For 2x2.5cm large reticule can accommodate 40x400 $\mu$ m pixels even with 350 nm process (AMS H35)
  - much finer pitch than hybrid solution (74.5  $\mu$ m)
  - current ABCN pipeline is 256 bits wide – need ~16 bits to store pixel address, hence could store 16 concurrent hits per BC
    - much more than necessary for average occupancy



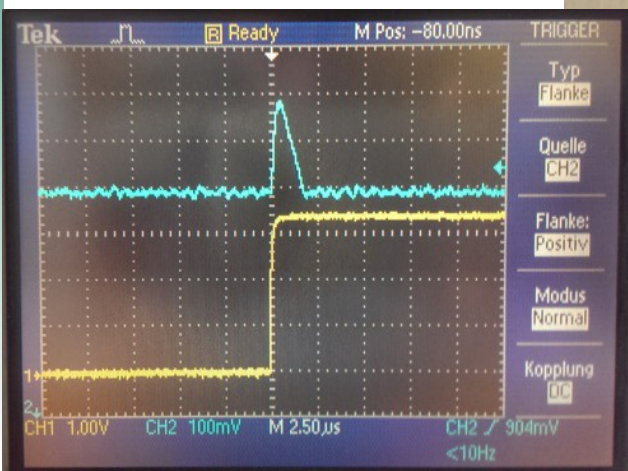
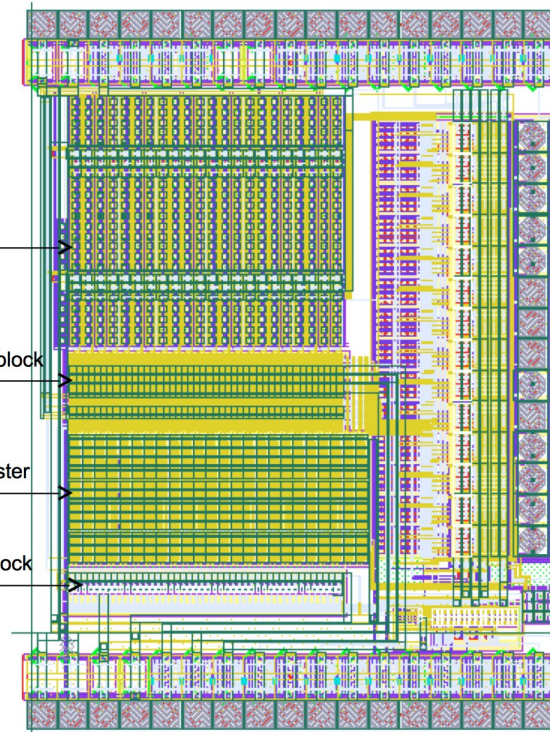
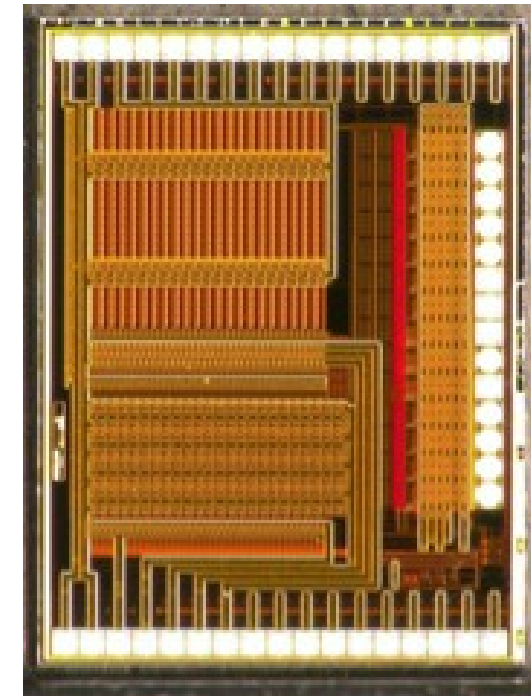
## First prototype

- H35\_v1
  - combines (very) small pixel array and test structures

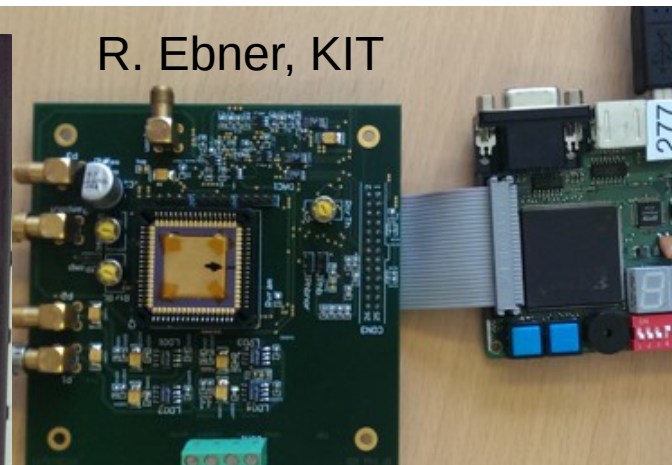


## First prototype

- H35\_v1
  - analogue  $40 \times 400 \mu\text{m}$  pixels with traces to the periphery
    - periphery not optimised and much larger than it would be in real size sensor (just few %)
  - discriminator block contain standard and “constant fraction discriminator”-like circuits aiming for improved time-walk
  - digital encoding, followed by 320 MBit/s LVDS readout, two concurrent hits can be read out
  - several test structures for rad-hardness testing
  - very first measurements being done, chip is alive – more to come

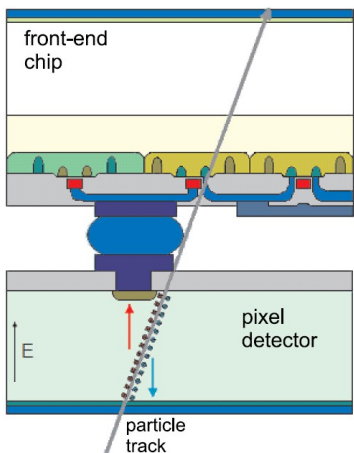


R. Ebner, KIT

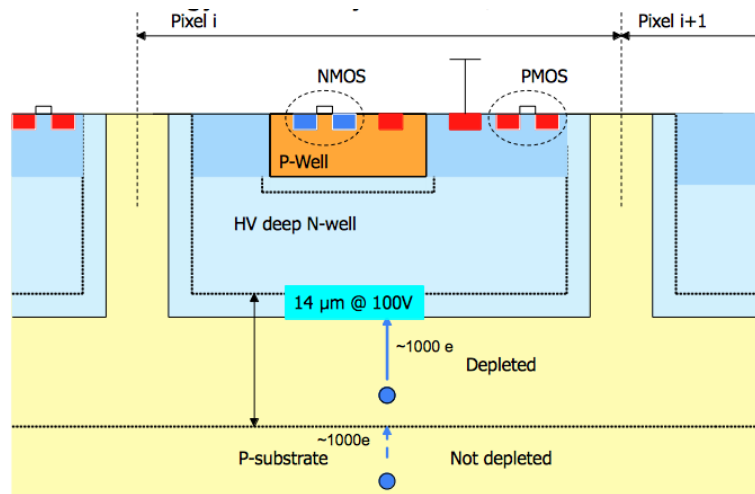


## HR-CMOS

- Main requirement for drift-based CMOS sensor is a deep n-well
  - also present in CIS (CMOS Image Sensor) processes with high-resistive substrate or epi layer → larger depletion depth
    - certainly larger initial signal, reduction of depletion depth to be studied
    - charge sharing possible again allowing to higher resolution at low fluences
- Several CMOS imaging processes available from different foundries
  - back-side illumination requires full depletion and thin sensors
  - high-resistivity FZ base material available in an industrialised process
- HV-CMOS appears to be “on the edge” wrt to Signal/Threshold
  - increase signal by more depletion? How much? Equally radiation-hard?
  - 2 directions: “moderate” (100 Ohm\*cm) vs. “high” (kOhm\*cm) resistivity

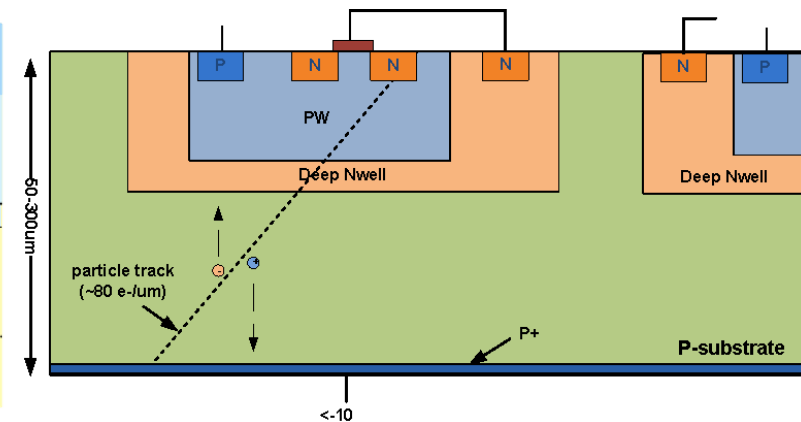


Hybrid



CMOS electronics placed inside the diode (inside the n-well)

HV-CMOS

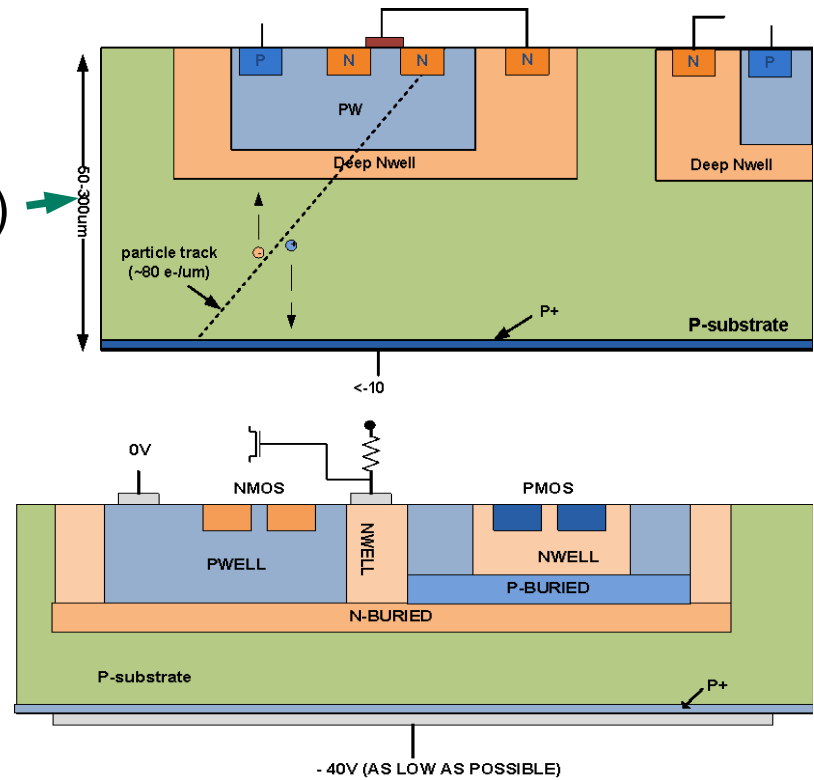
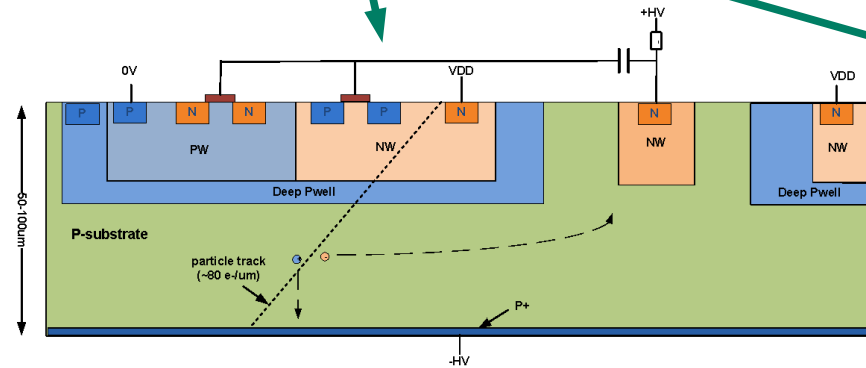


<-10

HR-CMOS

## HR-CMOS

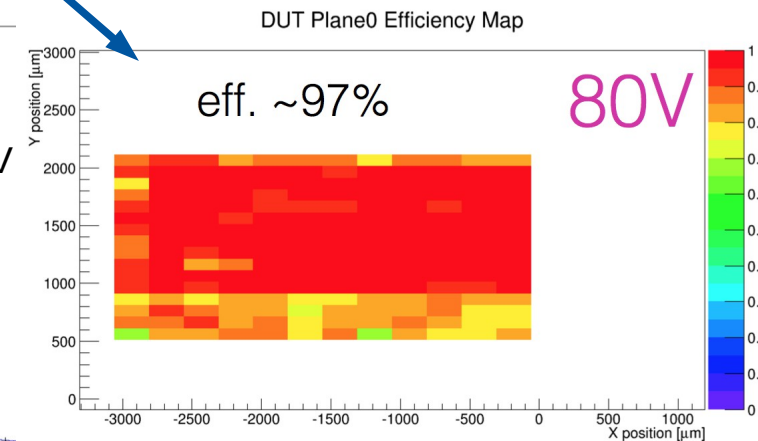
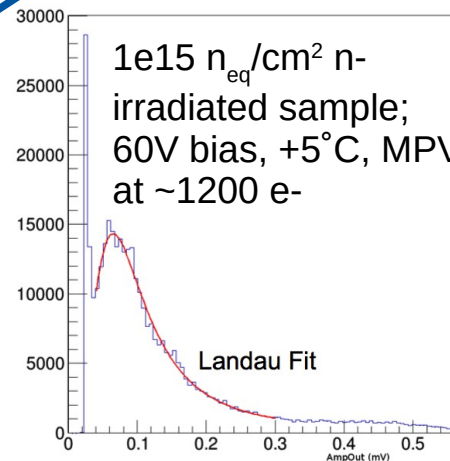
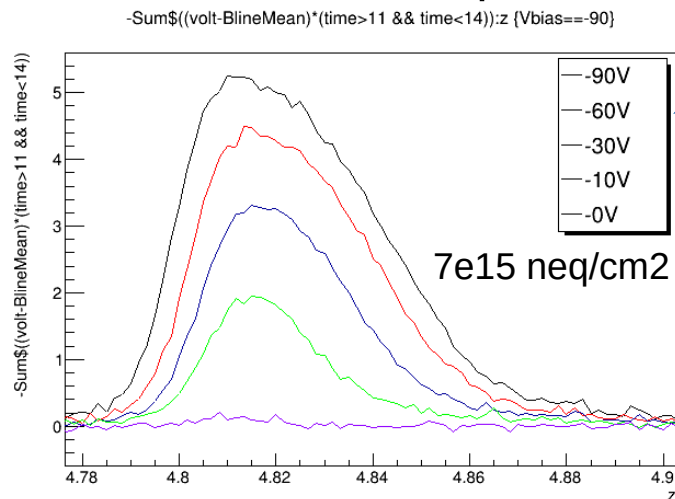
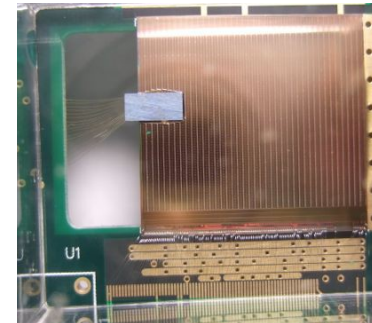
- Many different designs possible:
  - HV-CMOS like (deep n-well, no triple-well)
  - triple-well
  - Alice-like



- First prototypes have been produced within ATLAS
  - characterisation, irradiations ongoing
  - no time to go into detail
- “Moderate” resistivity submissions of “HV-CMOS” designs planned for early 2015
  - expect signal increase of a factor 2-5 while still being radiation-hard thanks to (comparatively) short drift lengths

## Conclusions

- HV/HR-CMOS processes might yield radiation-hard, low-cost, improved-resolution, low-bias-voltage, low-mass active pixel sensors
- Process can be used for
  - 'active' n-in-p sensors (with capacitive coupling)
  - drift-based close-to-MAPS chips (digitally encoded strips)
- First prototypes being explored within ATLAS
  - Irradiated samples show radiation hardness
  - results with capacitively coupled HV-CMOS pixel sensors look promising



- Next step: Explore higher resistive substrates to slightly increase signal
  - engineering run with large-scale sensor planned for early 2015
- (ATLAS) goal: Have “demonstrators” in hand by the end of 2015



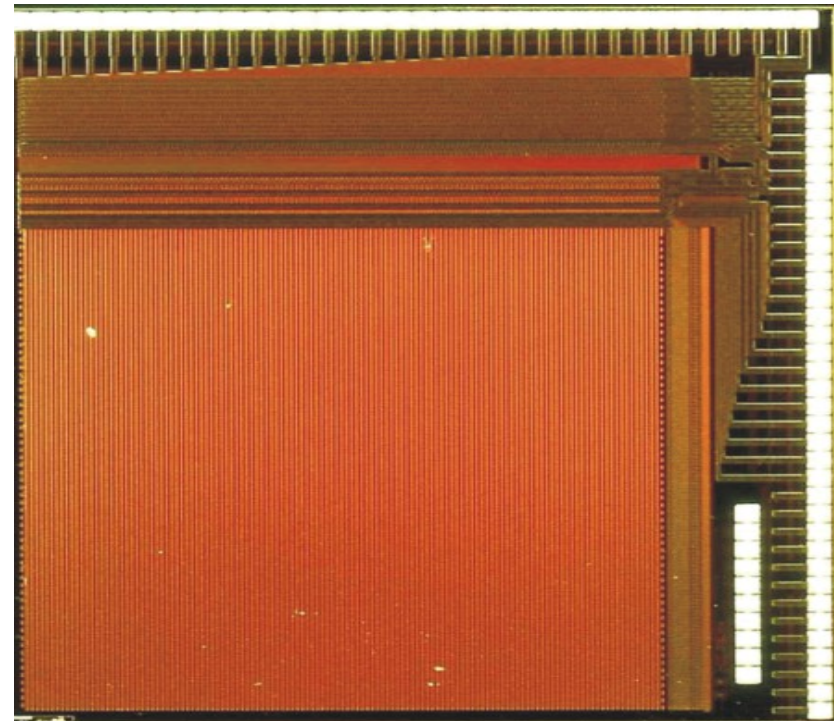


BACKUP SLIDES

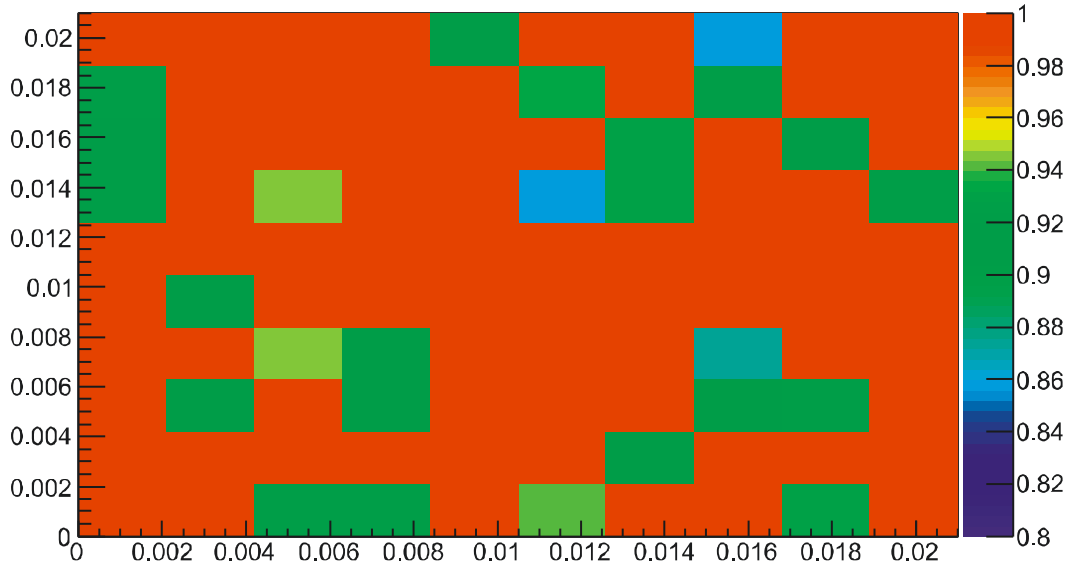


## Test beam results: monolithic

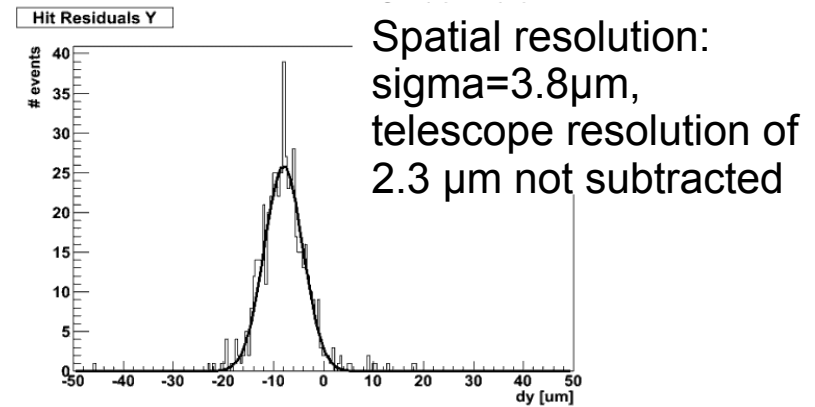
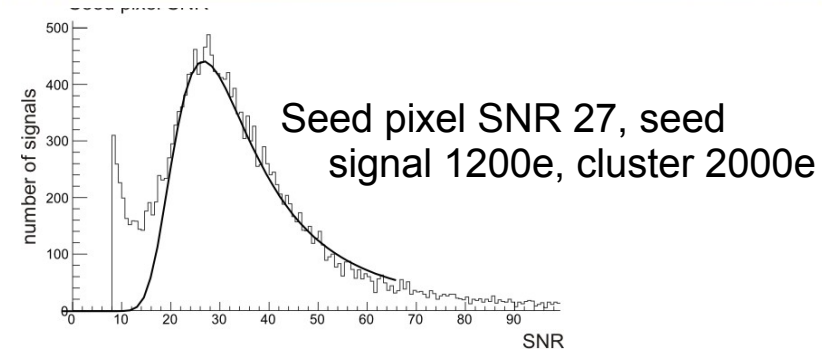
- excellent resolution
- very good S/N ratio
- efficiency limited by readout artifacts:
  - column-based readout
  - row not active during readout
  - data analysis did not correct for this
  - very small chip → low statistics



Efficiency vs subpixel particle position in X/Y

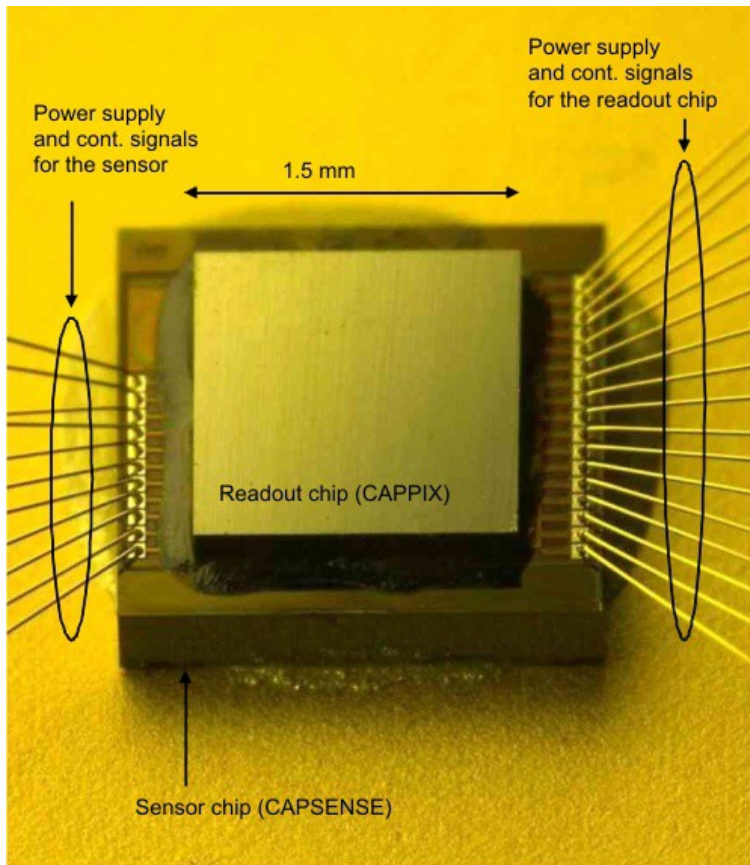


Efficiency vs. the in-pixel position of the fitted hit.  
 Efficiency at TB: ~98% (probably due to a rolling shutter effect)

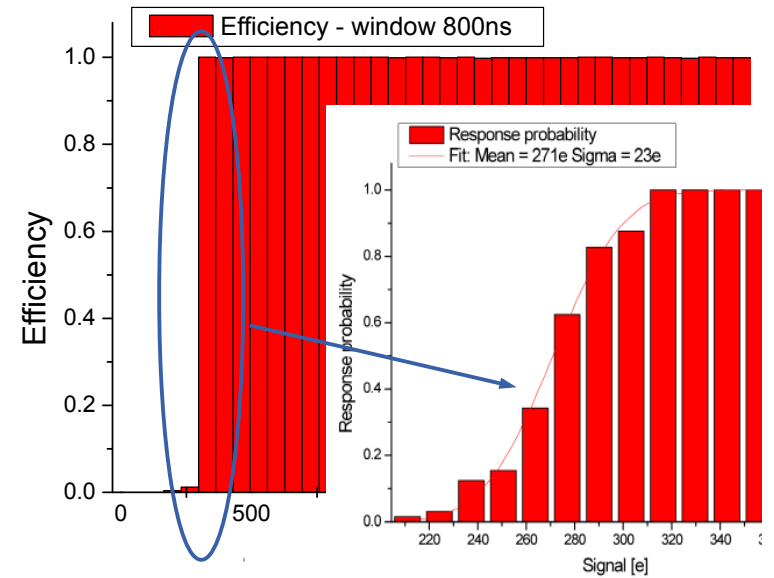


## CCPD prototype results

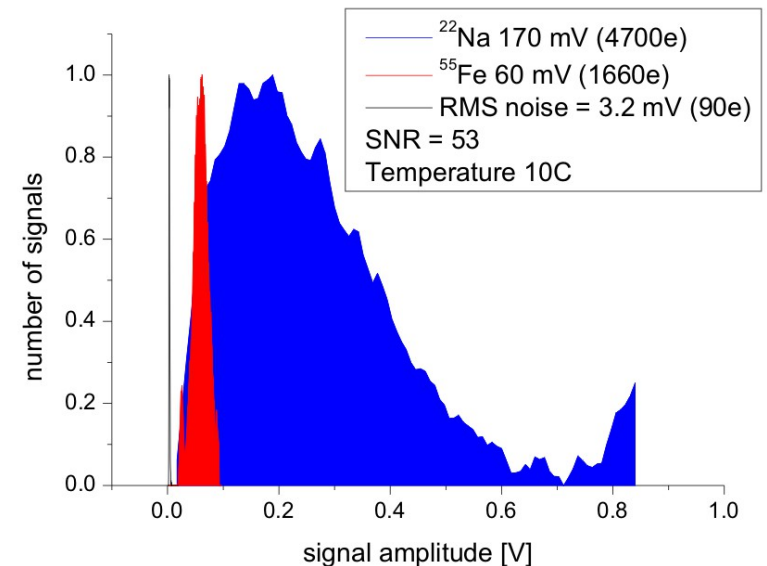
- excellent noise behaviour: stable threshold at  $\sim 330$  electrons
- good performance also after irradiation



CAPPIX/CAPSENSE edgeless CCPD  
50x50  $\mu\text{m}$  pixel size



Detection efficiency vs. amplitude  
Detection of signals above 330e possible with  $>99\%$  efficiency.



Signals and noise of a CAPSENSE pixel after  $10^{15} n_{\text{eq}}/\text{cm}^2$



## CPPD prototype results

- Irradiation with 23 MeV protons:  $1 \times 10^{15}$  neq/cm<sup>2</sup>, 150MRad
- FE-55 performance recovers after slight cooling

